

Rapid fabrication of advanced optics 1 foot² per hour

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Cranfield, Bedfordshire, England

Established Royal Air Force Base Cranfield in 1937

Revised as the UK's College of Aeronautics in 1946

Broadened activity and renamed Cranfield Institute of Technology in 1969

Rebranded as Cranfield University in 1996



Turnover of £170 million per annum

2500 staff : 2500 PhD/MSc students

Manage the UK's Military Defence Academy

Retain Aircraft design/build accreditation

Own and operate a Grade 3 Airfield

Strategic partners to: Rolls Royce, BAe Systems, Boeing, Airbus Defence and Space

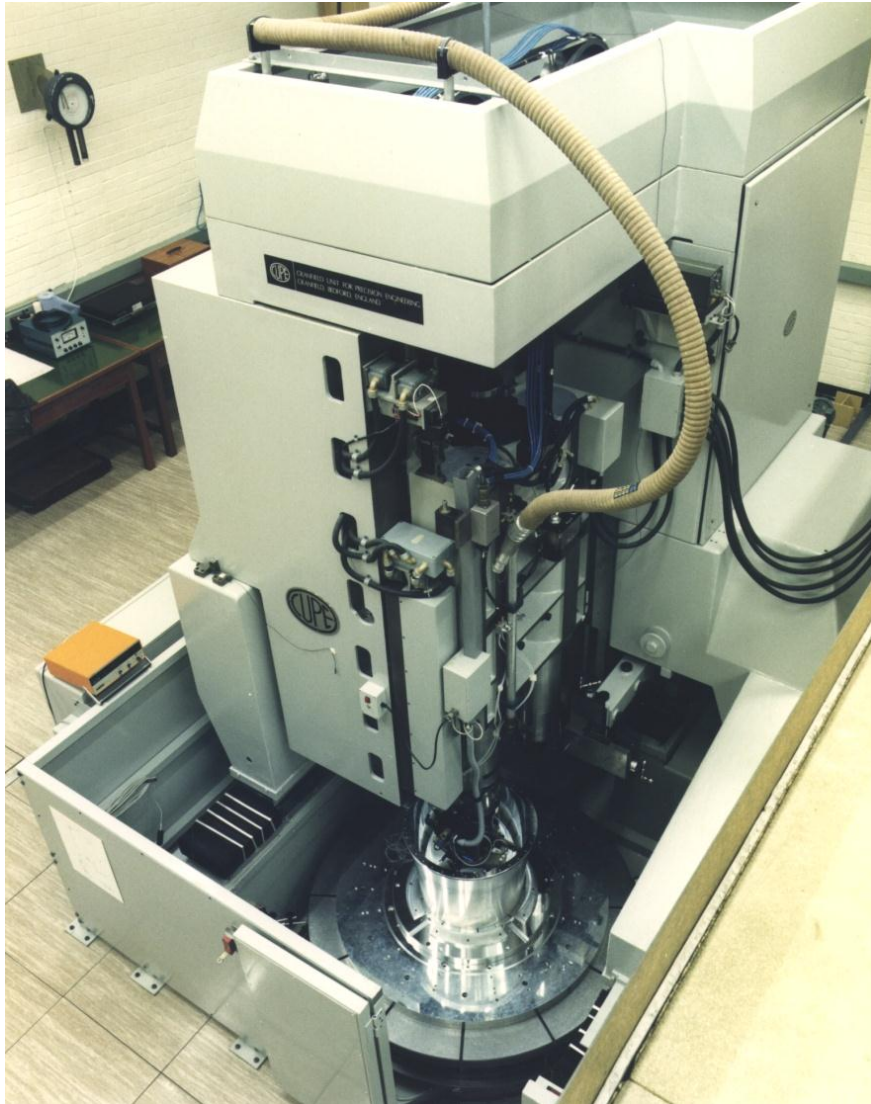
Approved supplier for ESA, NASA, ESO and NPL programmes



Talk structure

1. Cranfield previous mirror activities
2. 1 foot² per hour
3. Rapid freeform process chain
4. Freeform surface grinding
5. Reactive atom plasma surface figuring
6. Summary

Large Diamond Turning Machine for producing
X ray Astronomy Mirrors





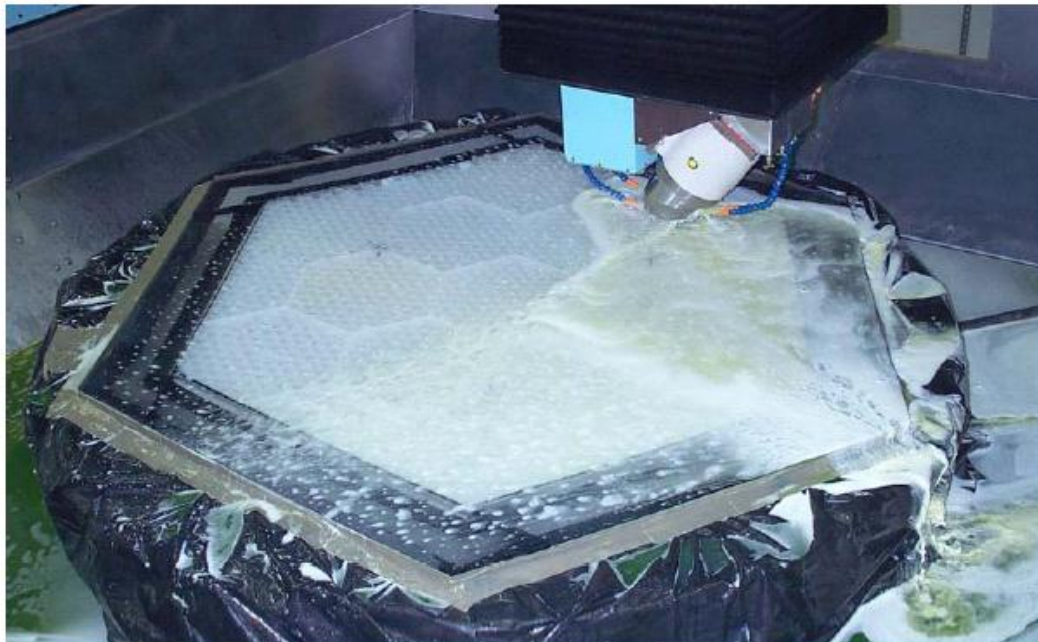
OAGM 2500





TAKE PICTURES. FURTHER.

Aspheric Generation

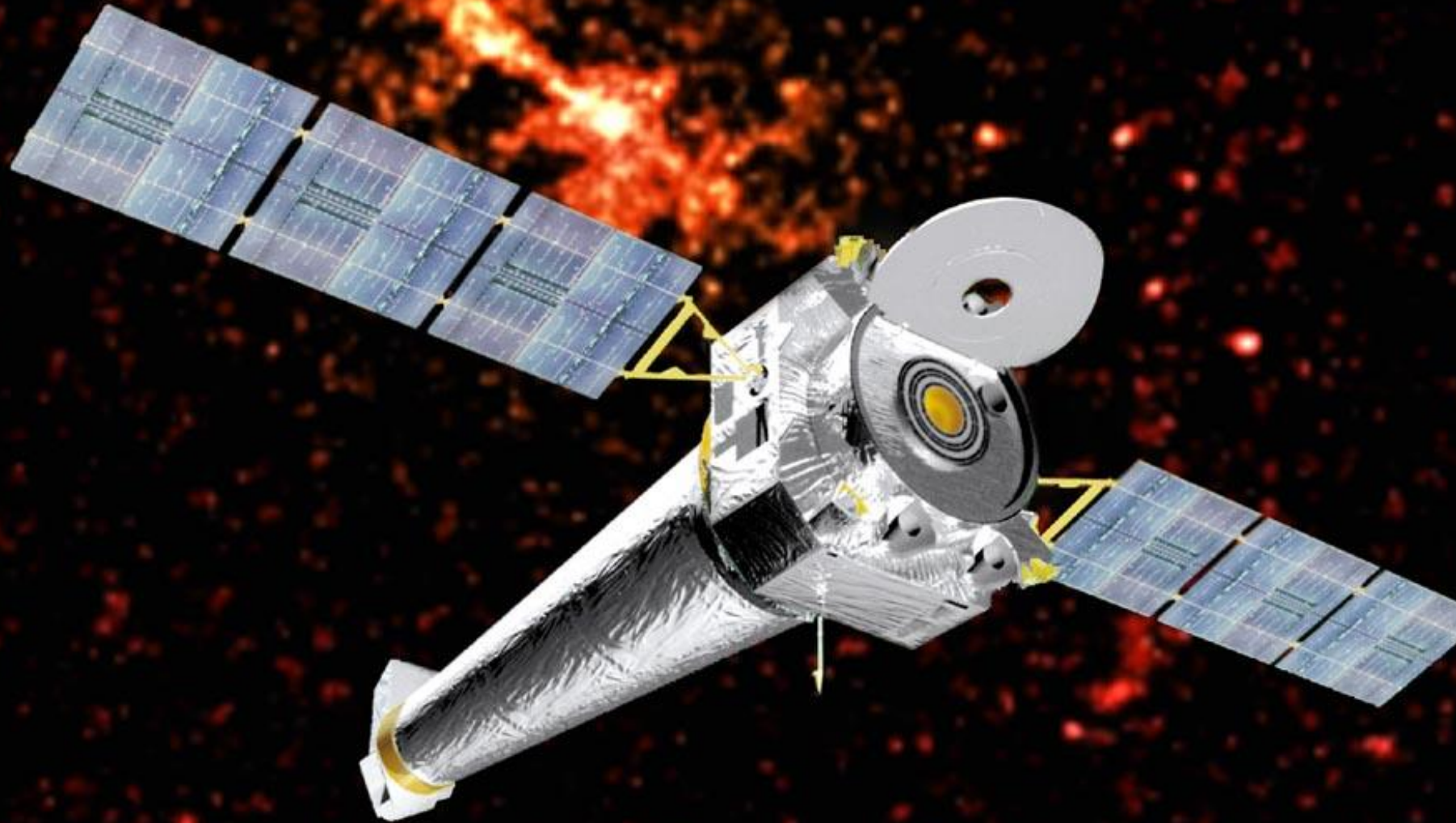


Off-Axis Generation Machine (OAG) used to impart final asphere onto AMSD mirror

10 micron P-V surface generated



Chandra X ray Space Telescope

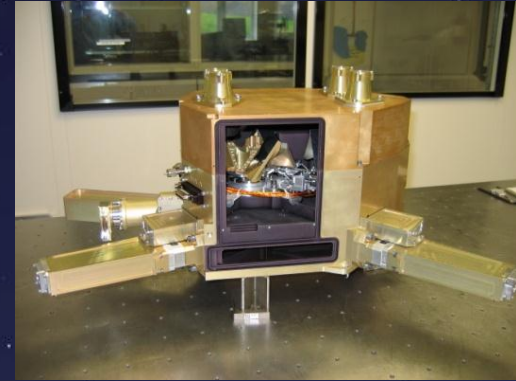
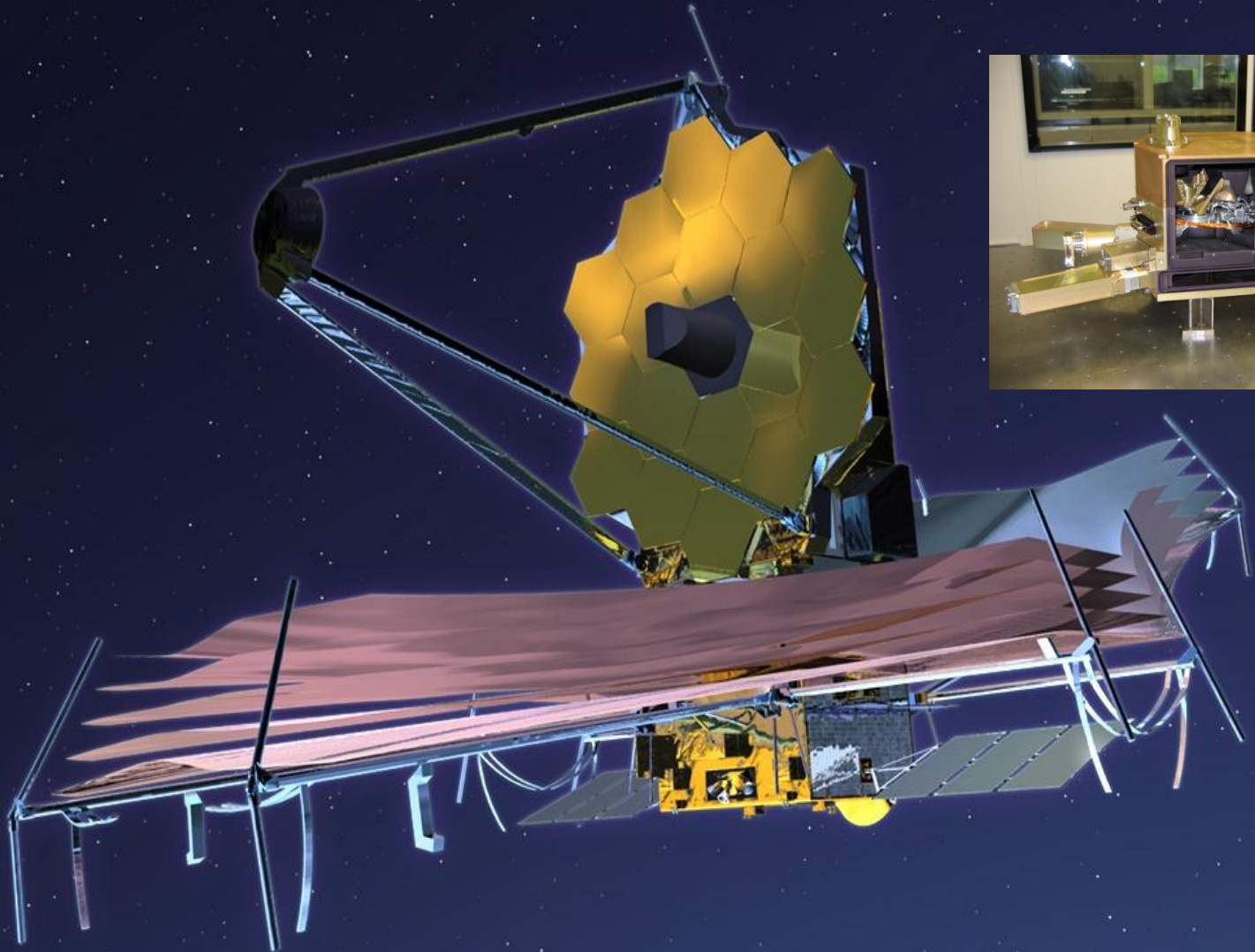


CUPE CIDI measuring machines made for Hughes Danbury for the "Chandra" X ray space telescope



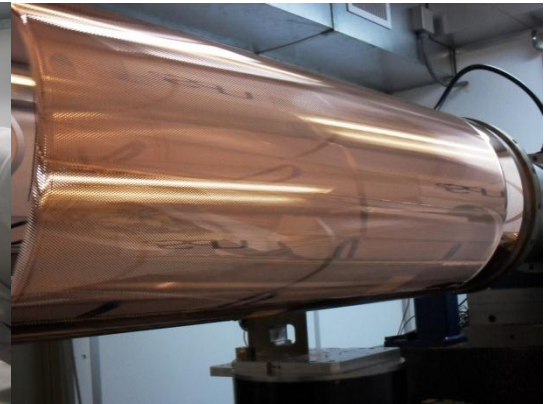
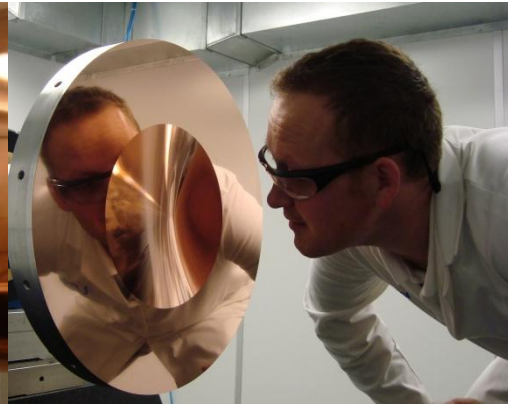
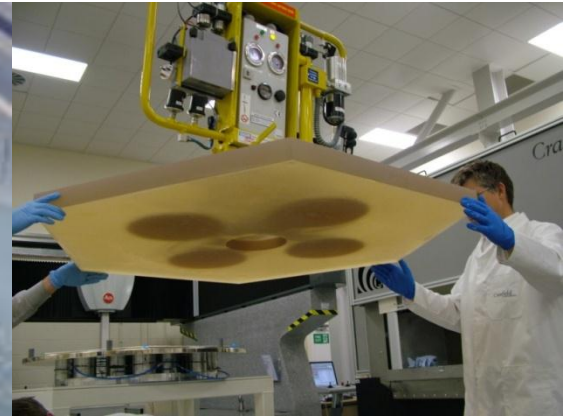
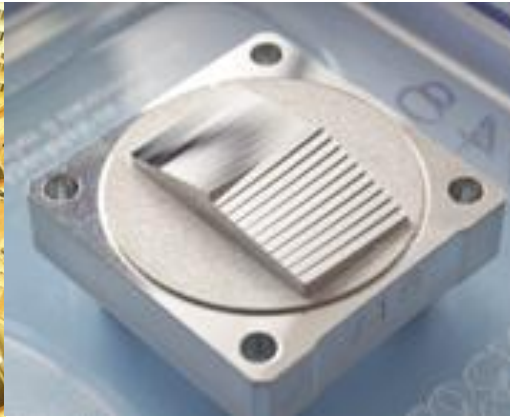
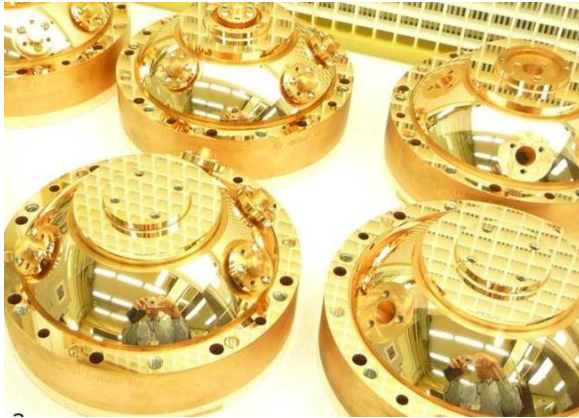
Ref; CUPE 1991

James Webb Space Telescope - MIRI Instrument Spectrometer Mirrors



JWST MIRI image slicer and re-imaging mirrors





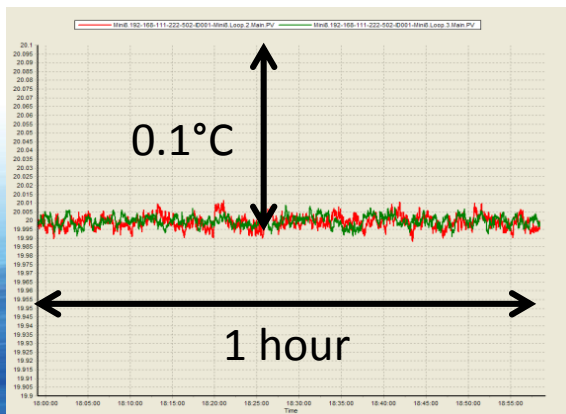
mK Ultra Precision Temperature Controllers



milli Kelvin Controllers

Loxham Precision's ultra precision temperature controllers are based on the most advanced thermal management technologies offering:

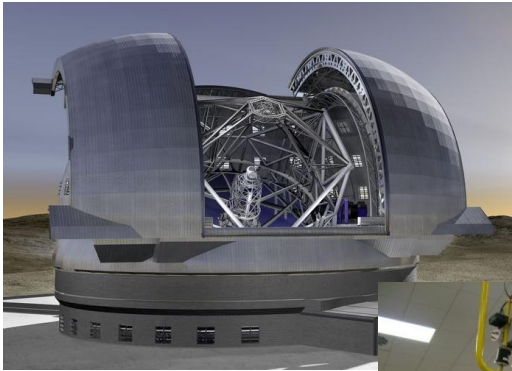
- Sub milli-Kelvin resolution control
- Multiple channels
- Matched performance temperature sensors
- High response cooling technology
- Advanced fluid heater technology
- Remote heater and sensor positioning
- Advanced control functions



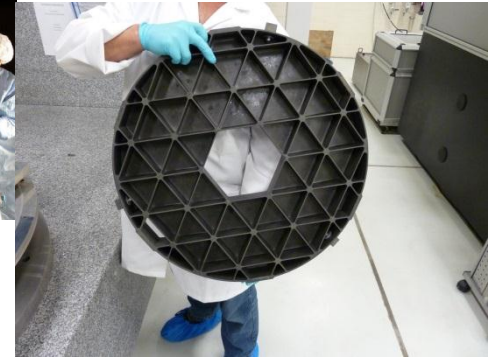
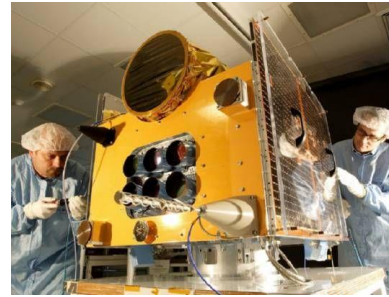
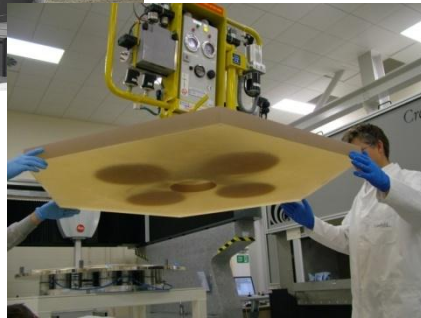
Pack	<input type="button" value="Start"/>	<input type="button" value="Stop"/>	Running <input checked="" type="radio"/>	Stopped <input type="radio"/>	Alarm <input type="radio"/>	Warning <input type="radio"/>						
Pump	<input checked="" type="button" value="Start"/>	<input type="button" value="Stop"/>	<input checked="" type="radio"/>				Pump Pressure [Bar]	<input type="text" value="29.3"/>	Pump Current [Amps]	<input type="text" value="1.5"/>		
Refrigeration	<input checked="" type="button" value="Start"/>	<input type="button" value="Stop"/>	<input checked="" type="radio"/>				Refrigeration HP [Bar]	<input type="text" value="6.3"/>	Refrigeration LP [Bar]	<input type="text" value="0.8"/>	Compressor Current [Amps]	<input type="text" value="1.3"/>
Rotary Heater	<input checked="" type="button" value="Start"/>	<input type="button" value="Stop"/>	<input checked="" type="radio"/>							Rotary Heater Current [Amps]	<input type="text" value="1.6"/>	
Linear Heater	<input checked="" type="button" value="Start"/>	<input type="button" value="Stop"/>	<input checked="" type="radio"/>							Linear Heater Current [Amps]	<input type="text" value="2.6"/>	

**Production rate : 1 foot² per hour
(1 metre² per 10 hours)**

Freeform optics



**Telescopes -
ELT**



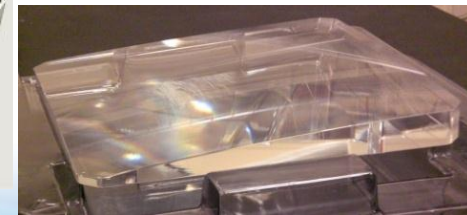
Space – Earth orbiters



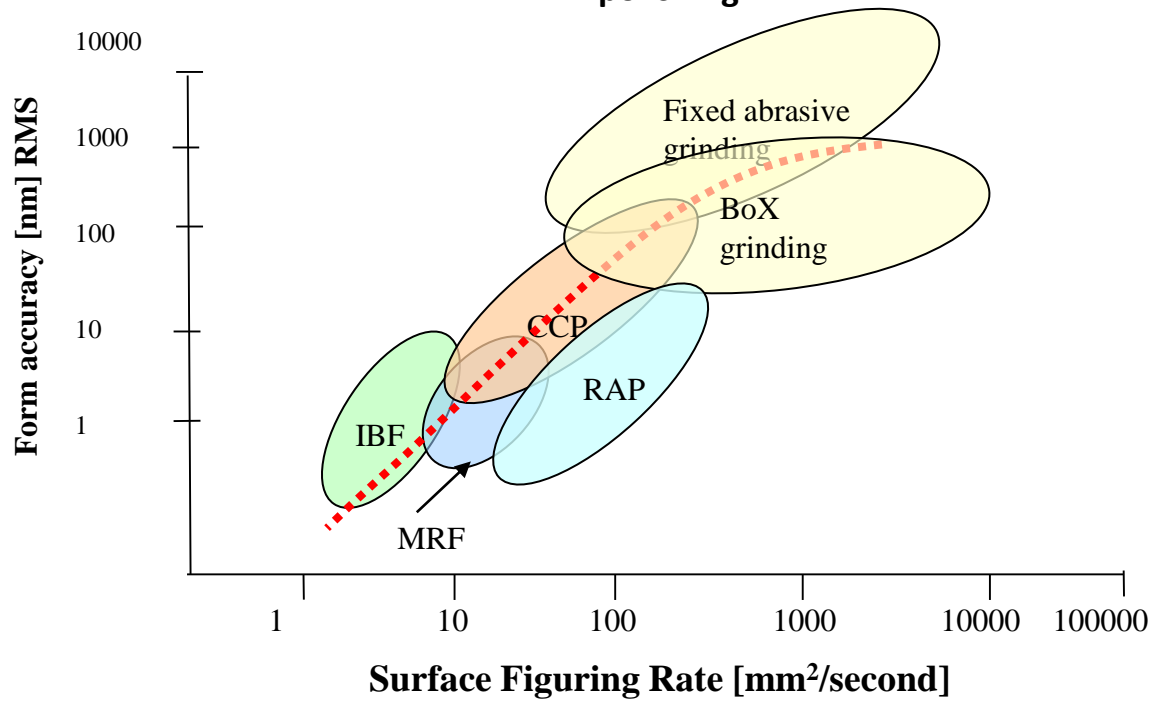
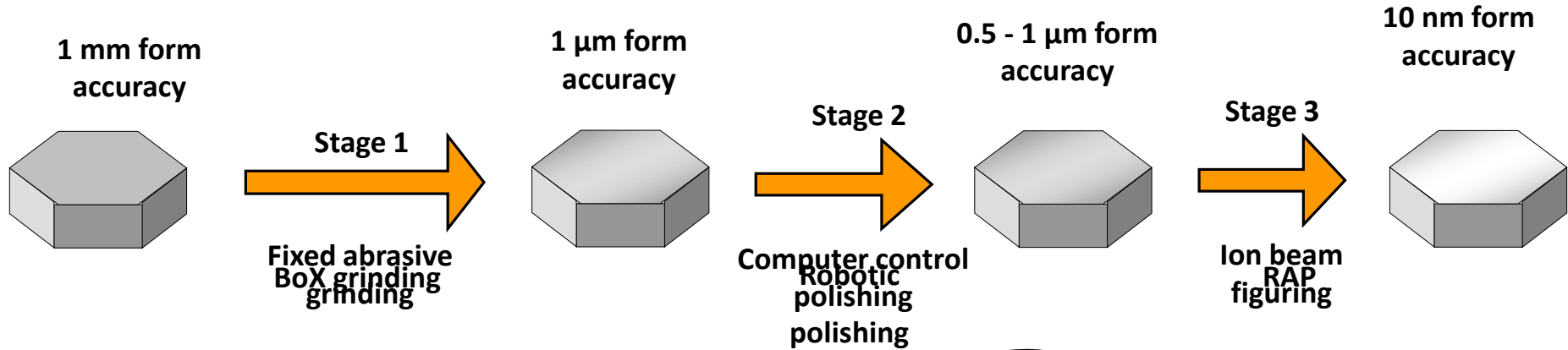
**Lithography - EUV
microlithography Systems**



Fusion – High power laser optics



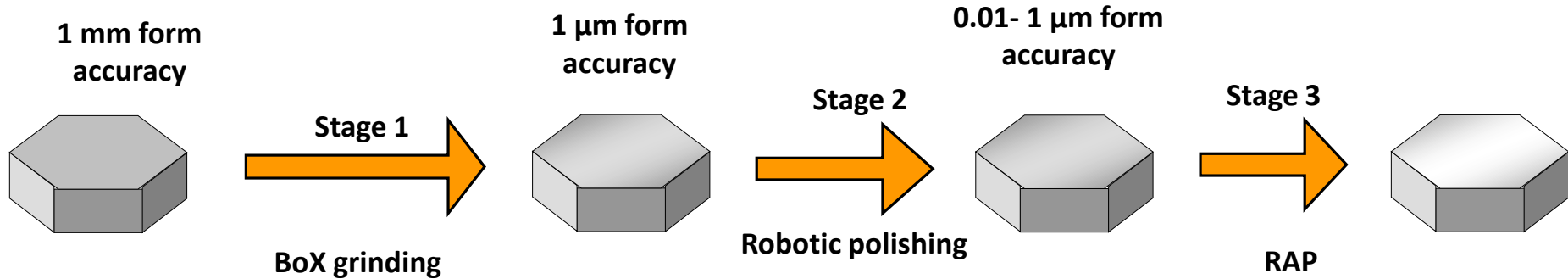
UPS Project Rapid Process Chain *Cranfield* UNIVERSITY



Rapid Process Chain

Requirement: 10 hours per 1m² (1ft² per hour or 1 E-ELT segment per day)

10 nm form accuracy



Grinding:

- Remove min 1mm depth
- Output visible by full aperture interferometry (P-V < 3 μm)
- Minimum sub-surface damage

Polishing:

- Remove SSD
- 1 nm RMS roughness
- Form accuracy <0.5 μm P-V (as time allows)

Re-active atom plasma:

- Remove min 2 μm depth
- Form accuracy 10nm
- Degrade roughness < 2 nm RMS

**Freeform surface grinding at 1 foot² per hour
(1 metre² per 10 hours)**

BOX[®] Freeform grinding/measuring machine

Work-piece quality

Form accuracy: < 1 μm RMS

Sub-surface damage: < 5 μm

Roughness: 100 - 200 nm

(Zerodur data)

Processing rate

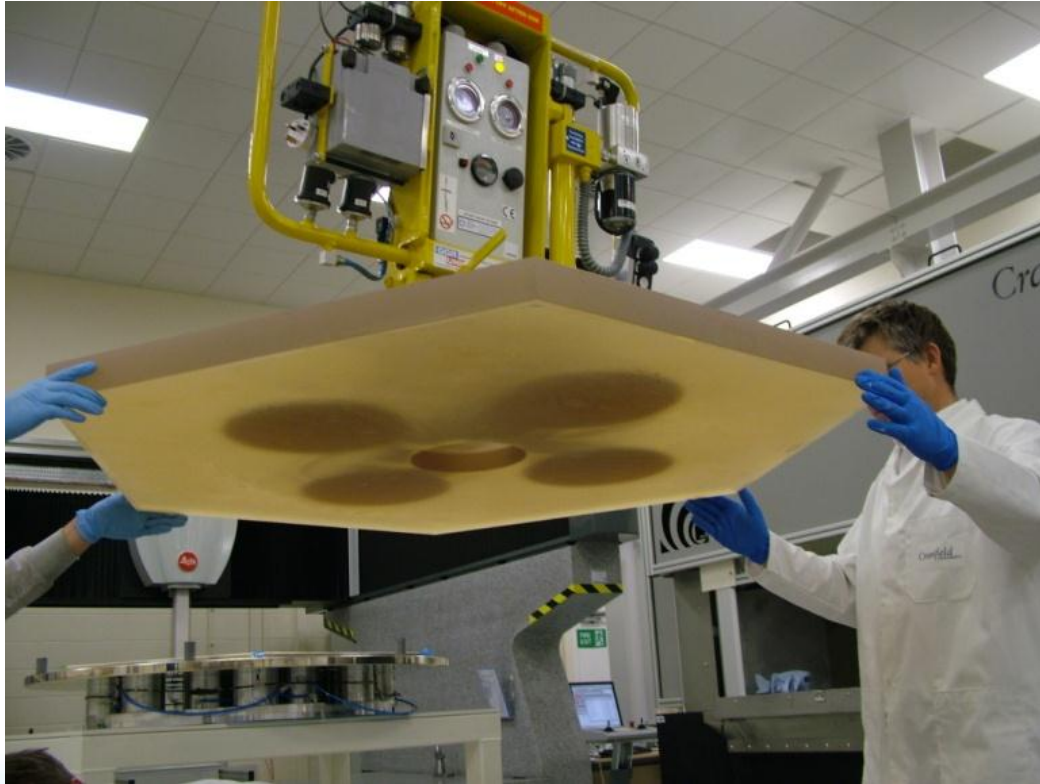
Grind time: 10 hrs/m²

Measurement time: 4 hrs/m²

Load/set/unload time: 1 hour



EELT Mirror segment



Watch Youtube video

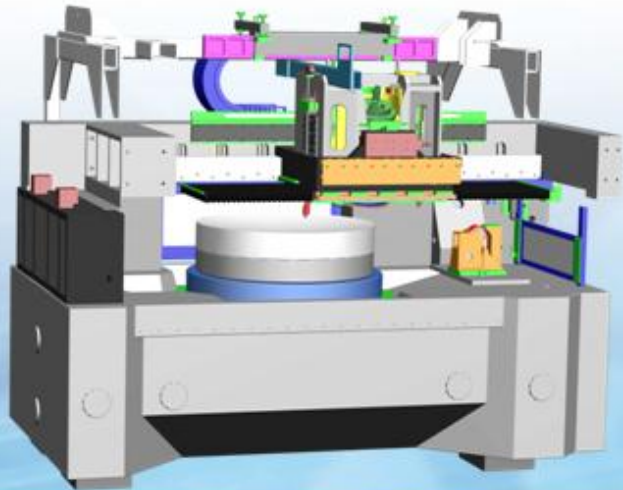
Search “Loxham Precision”

<https://www.youtube.com/watch?v=TBvFTmYzUYQ>

BoX® Ultra Precision 1600

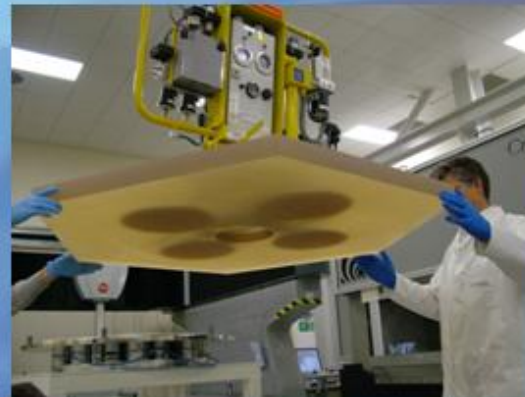
Freeform grinding & measuring machine

LOXHÅM
PRECISION

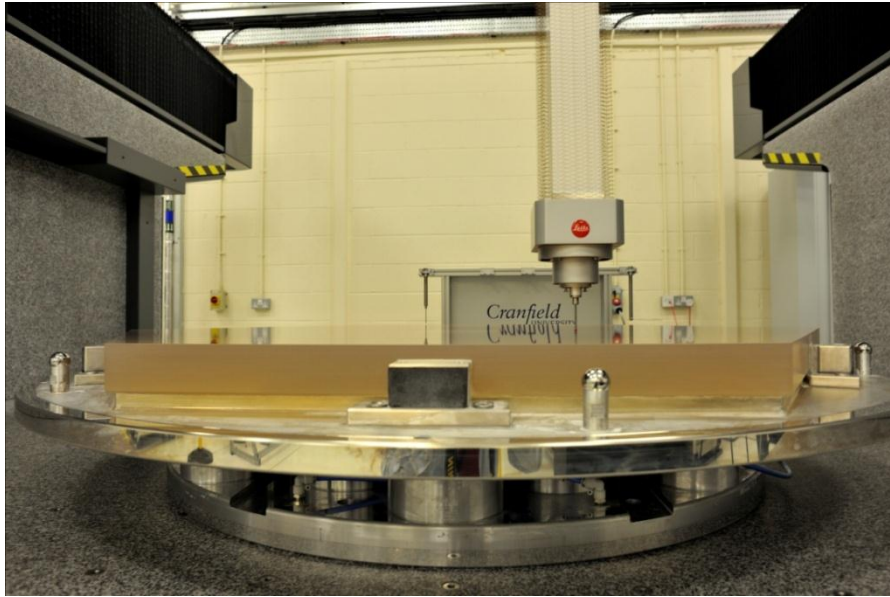


Deterministic ultra precision production technology to rapidly grind large optics of complex shape

- Proven freeform surface generation
- Unrivalled form accuracy capability
- Rapid processing rates
- Reduced levels of sub-surface damage
- Low cost of ownership



BoX[®] EELT Mirror segment (1)

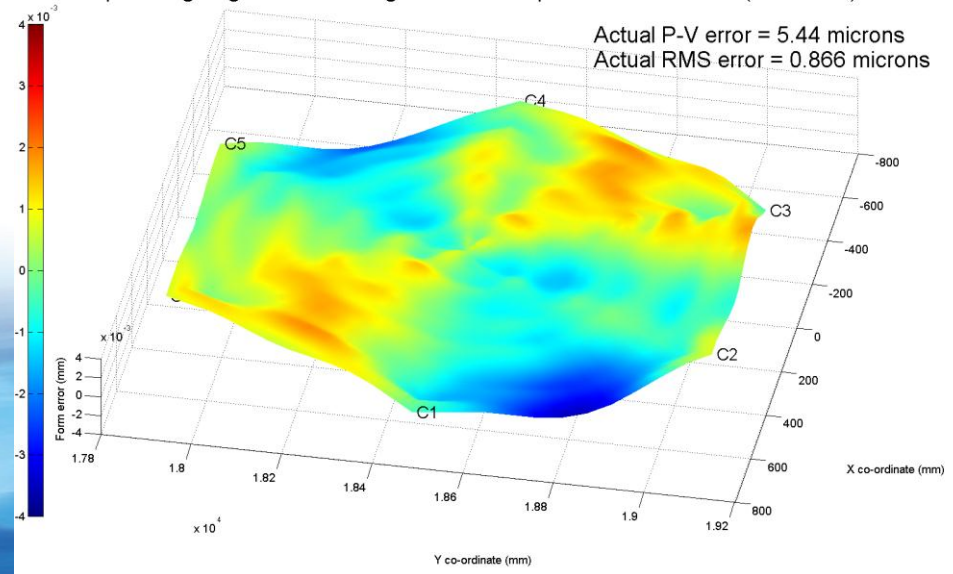


Results:

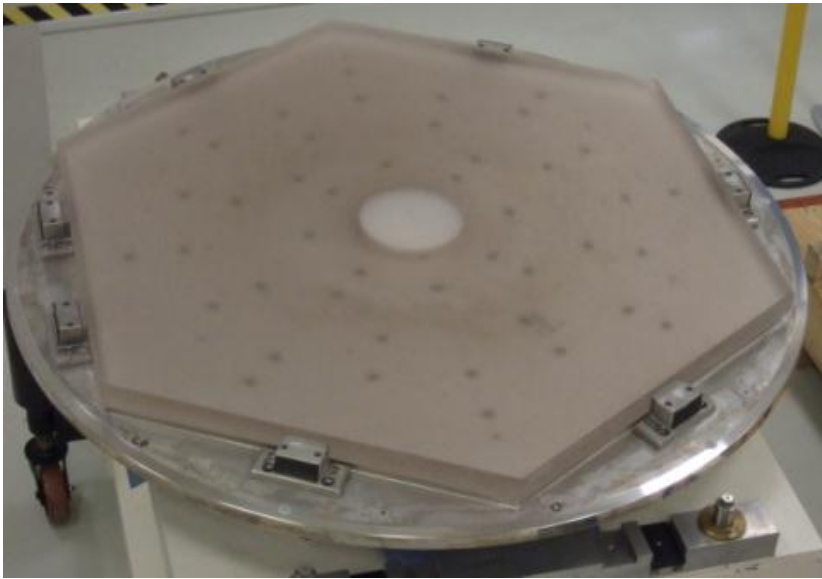
- Surface map (CMM)
- RMS < 1 μm , P-V < 5.5 μm
- No visible edge chipping
- No attributable cavity effect

- ELT segment SPN01 (15:15)
- Material – Zerodur
- 580,000 measurement points
- Data to within 0.5mm of edge

Aspherising Segment 1 - finish grind - error map in M1 co-ordinates (smoothed)



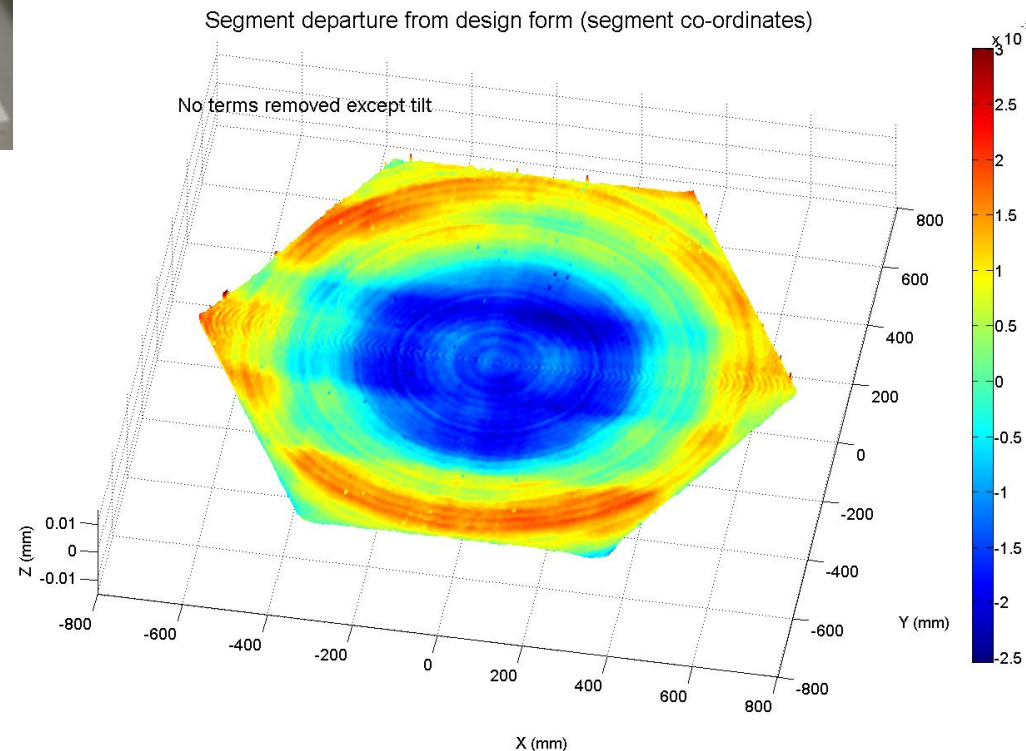
BoX[®] EELT Mirror segment (2)



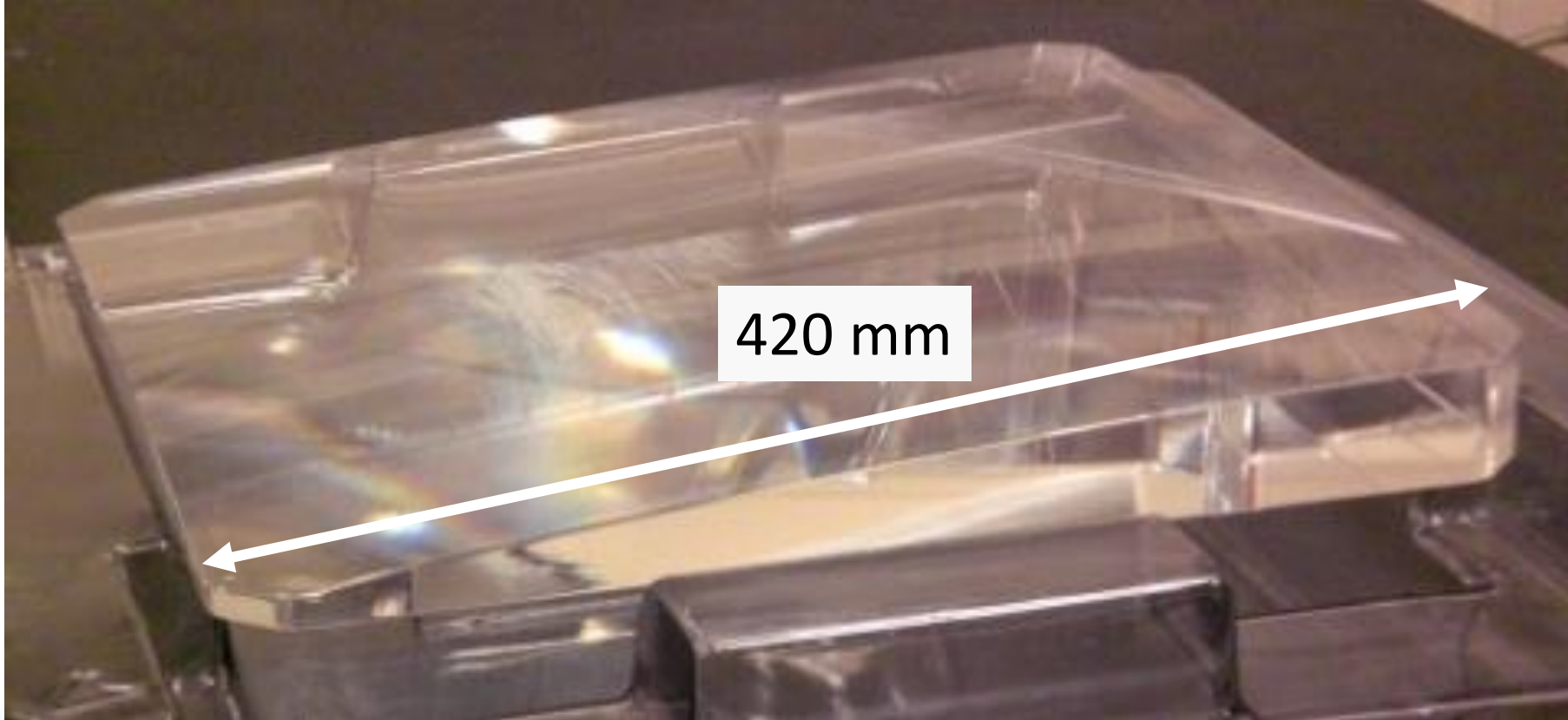
- ELT segment SPN04 (16:15)
- Material – ULE
- Grinding cycle 20 hours
- Max MMR 187.5mm³/sec

Results:

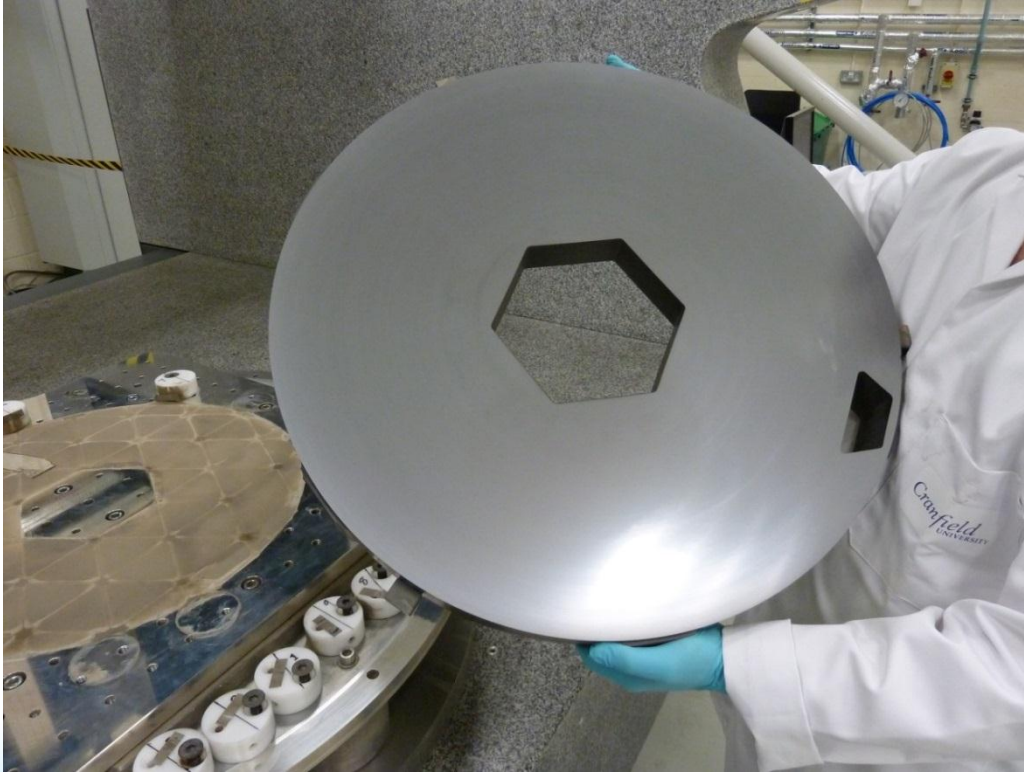
- Surface map (CMM)
- 580,000 measurement points
- RMS < 0.6 μm
- PV < 4.5 μm



BoX[®] NiF Wedge Optic Lenses



BoX[®] Adaptive grinding of lightweight mirror structures



Thinned from 6mm
to 1.3 mm shell thickness

Grinding time: 16 hours

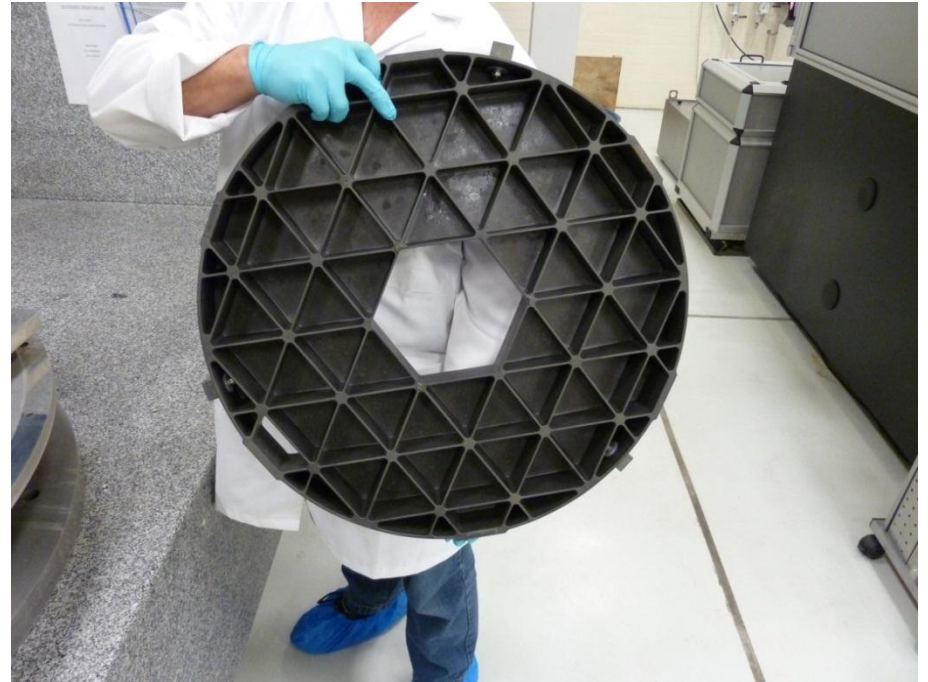
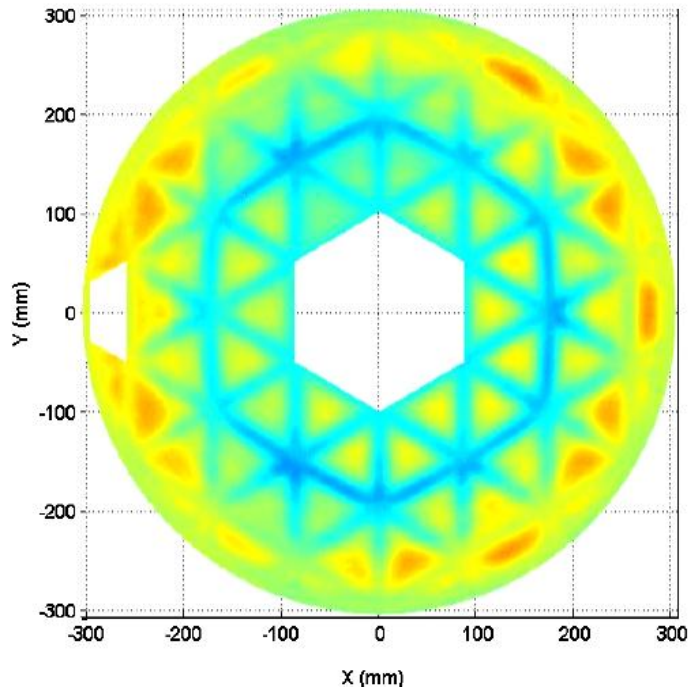
Measurement time: 4 hours

Form accuracy : 0.48um RMS

SSD : 5um

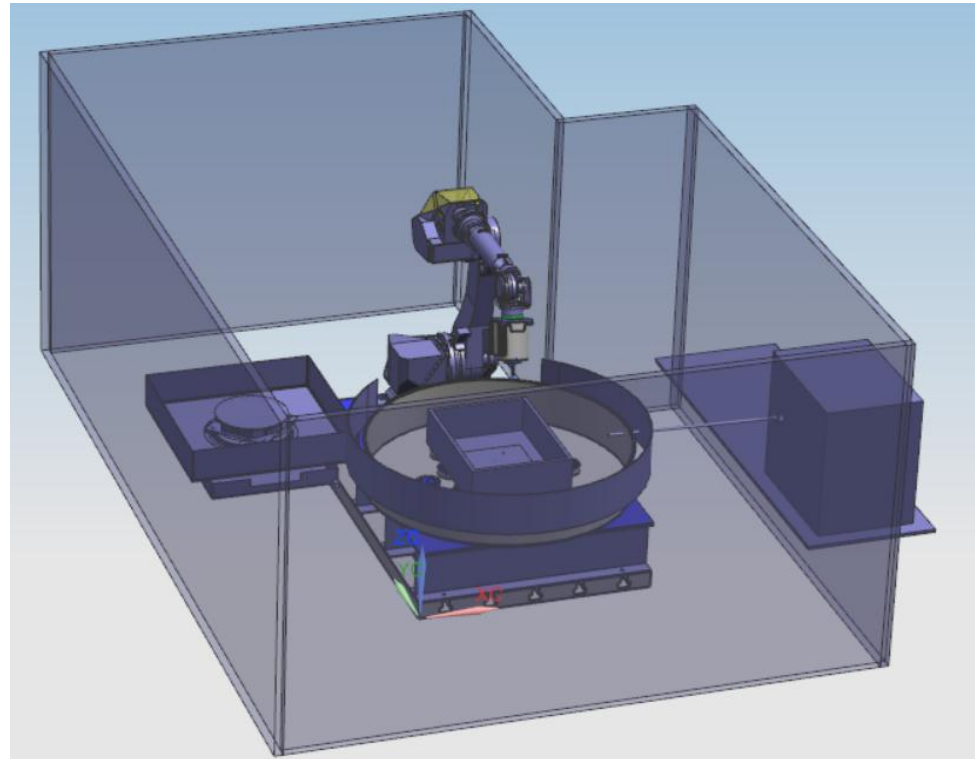
Roughness:0.15um RMS

BoX[®] Adaptive grinding of lightweight mirror structures



0.4 μ m RMS, 4.6 μ m P-V
(before error correction)

Robotic polishing



Reactive Atom Plasma (RAP) Processing: A New Tool for the Rapid Shaping and Smoothing of Optical Materials

Dr. Peter S. Fiske

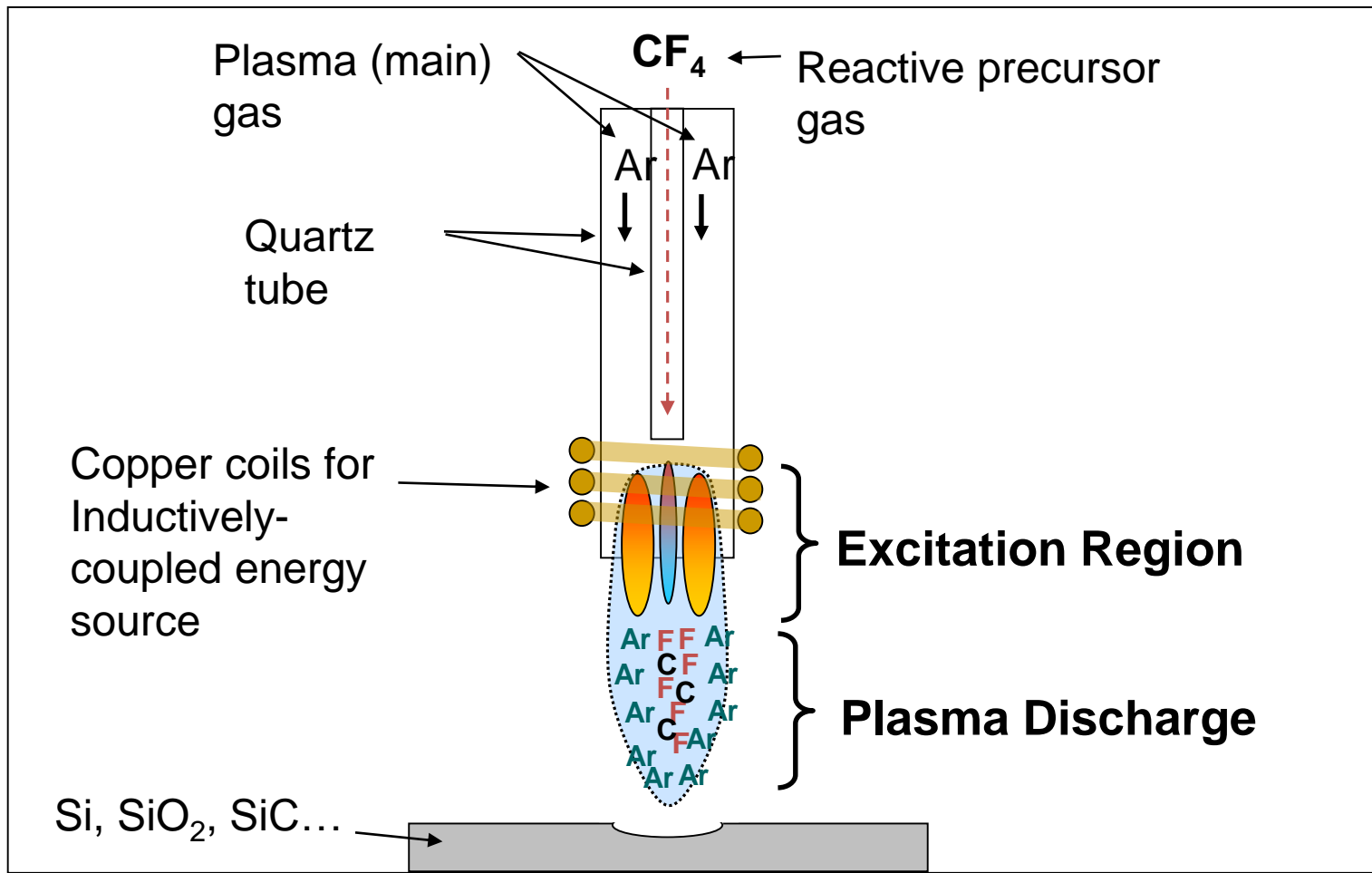
Dr. Jeff Carr

Dr. Andrew Chang

Dr. Jude Kelley

RAPT Industries

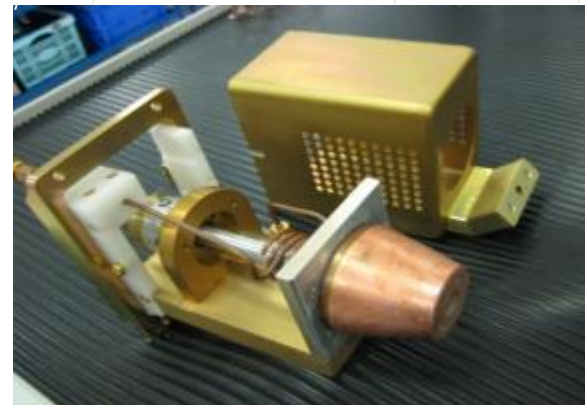
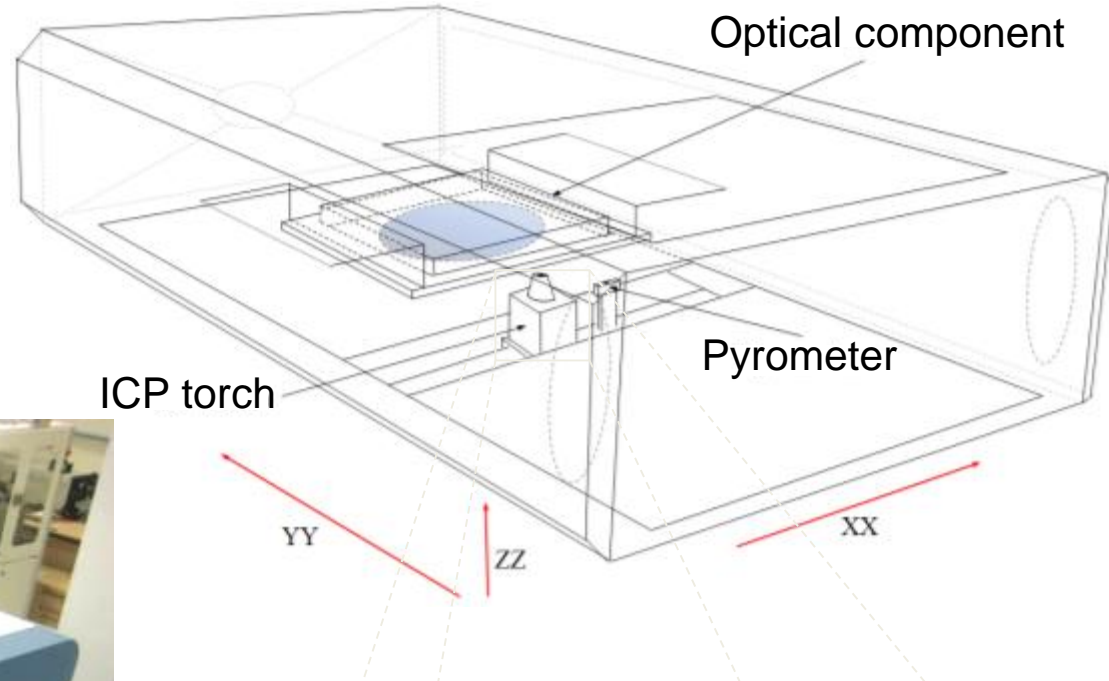
Livermore, California



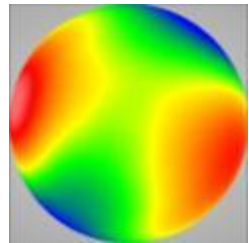
Courtesy Carr

Reactive Atom Plasma Figuring Helios 1200

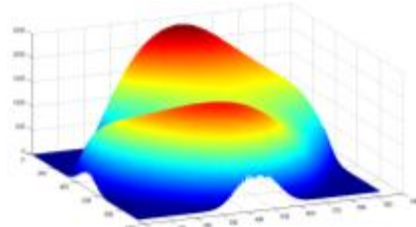
Chamber for 1.2 m
optical component



Iterative figuring procedure



Error map



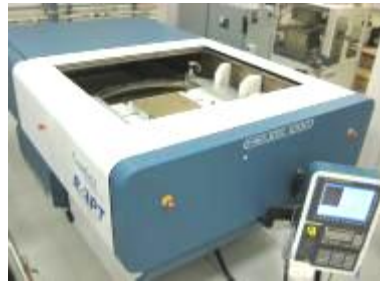
Edge extension



De-convolution
(modified)



CNC-code generation with
optimized tool-path and
thermal adaption



RAP process

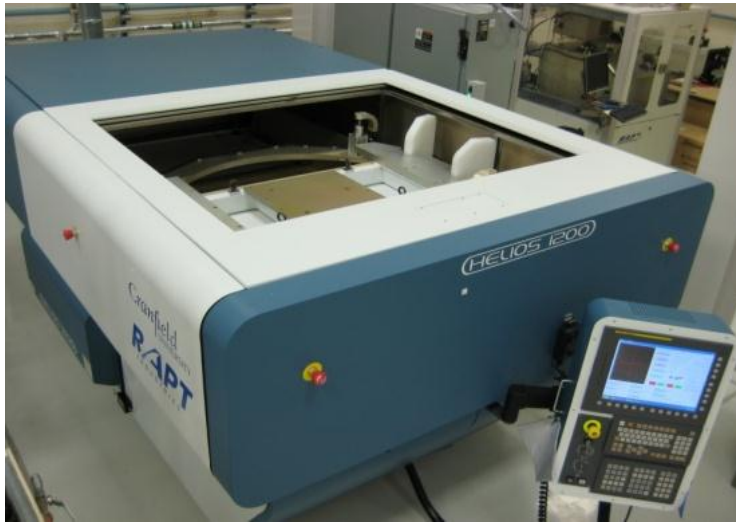


Interferometric
measurement



Final form accuracy down to $\lambda/30$ rms

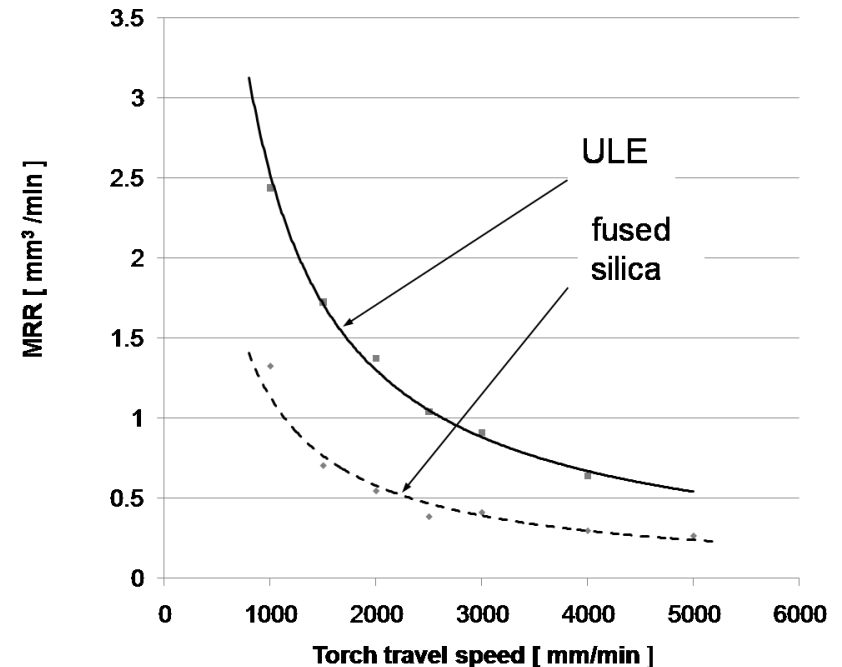
RAP process capability



- 1.2 m capacity
- 3 axes CNC through Fanuc 30i
- Low cost operation
- Compact machine size

Processed materials:

- Fused silica
- ULE
- SiC
- Silicon
- Borosilicate

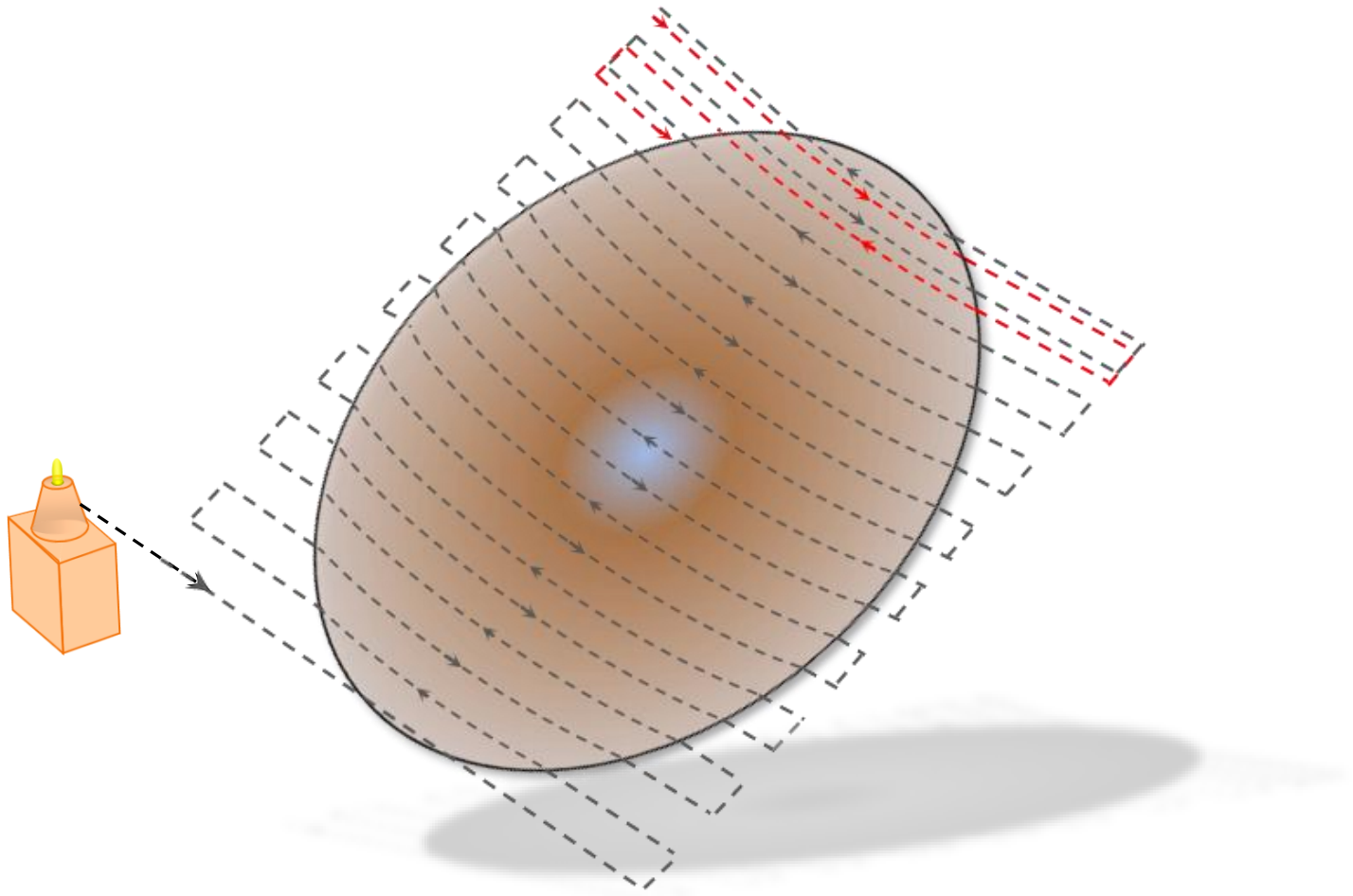


Refs

1: Jourdain et al., (2011). "Fast 3D Figuring of Large Optical Surfaces Using Reactive Atom Plasma (RAP) Processing", 2nd EOS Conference on Manufacturing of Optical Components, Munich (D), May 2011.

2: Castelli et al., (2010). "Initial Strategies for 3D RAP Processing of Optical Surfaces Based on a Temperature Adaptation Approach" 36th Matador Conference, Manchester, section:18, pp 569-572 , July 2010

Tool-path algorithm

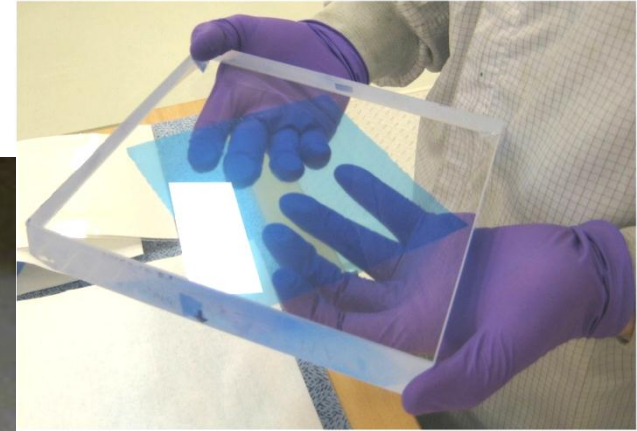


RAP figuring process

0.5 um depth of cut



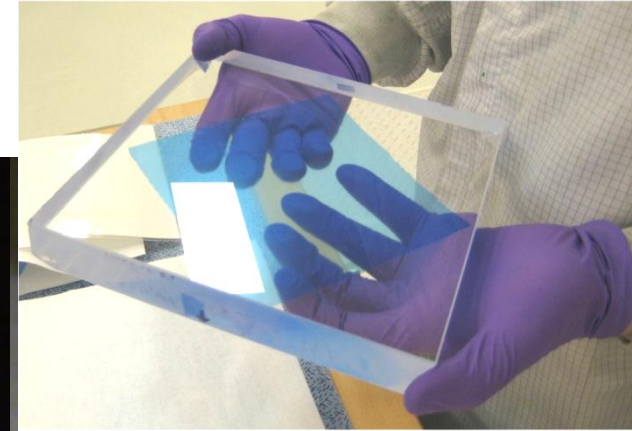
Cranfield
UNIVERSITY



Fused Silica

RAP figuring process

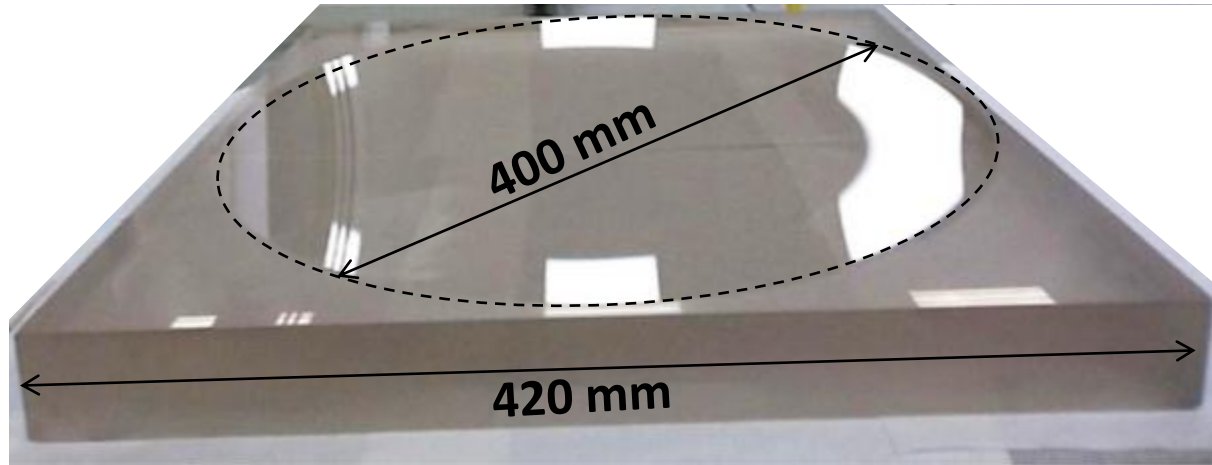
0.5 μm depth of cut



Fused Silica



RAP figuring capability

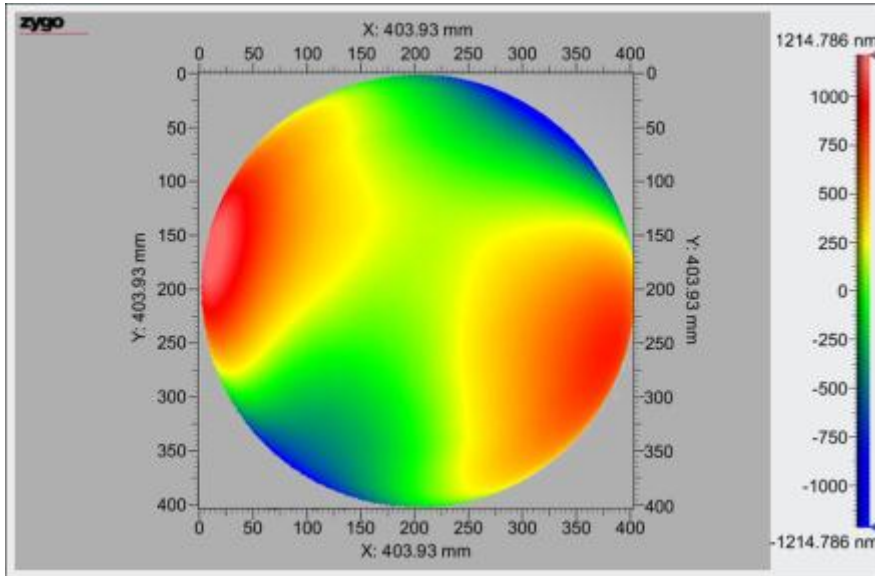


420mm x 420mm x 40mm ULE substrate

- Concave spherical geometry – 3 m ROC.
- 400 mm clear aperture.
- Ground on BoX to $\sim 2.2 \mu\text{m}$ PV form accuracy.
- Polished to $2.4 \mu\text{m}$ PV form accuracy.

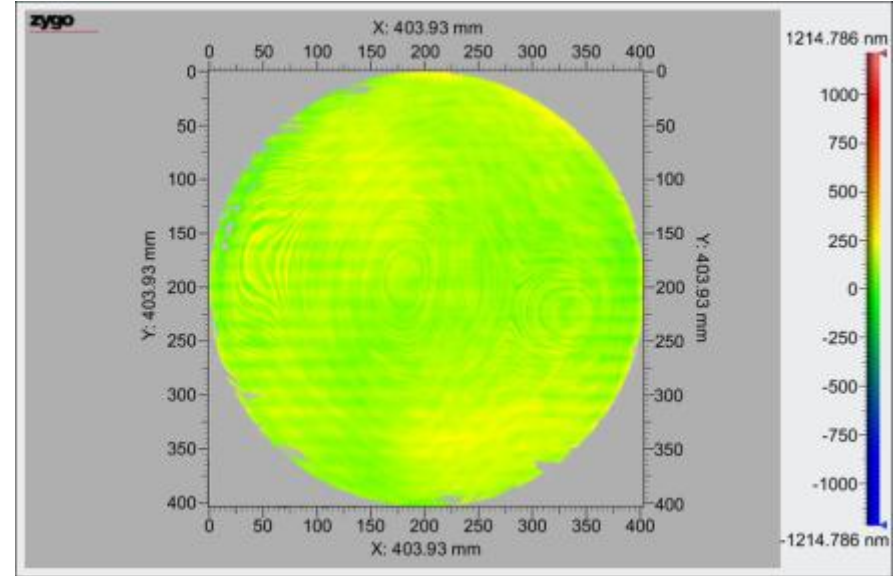
Large scale figuring results: optic #001/1

Initial figure error



PV: 2.4 μm PVr: 2.3 μm RMS: 373 nm

Residual figure error

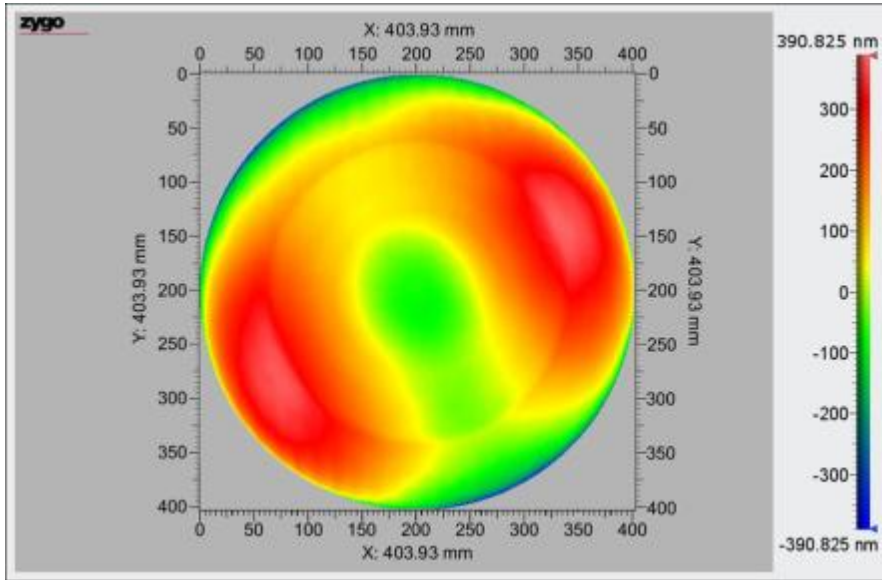


PV: 450 nm PVr: 282 μm RMS: 45 nm

- Mean processing time: 51 min - three iterations → **total processing time 2.5 hours**
- Residual figure error: 43 nm rms
- 89% overall convergence

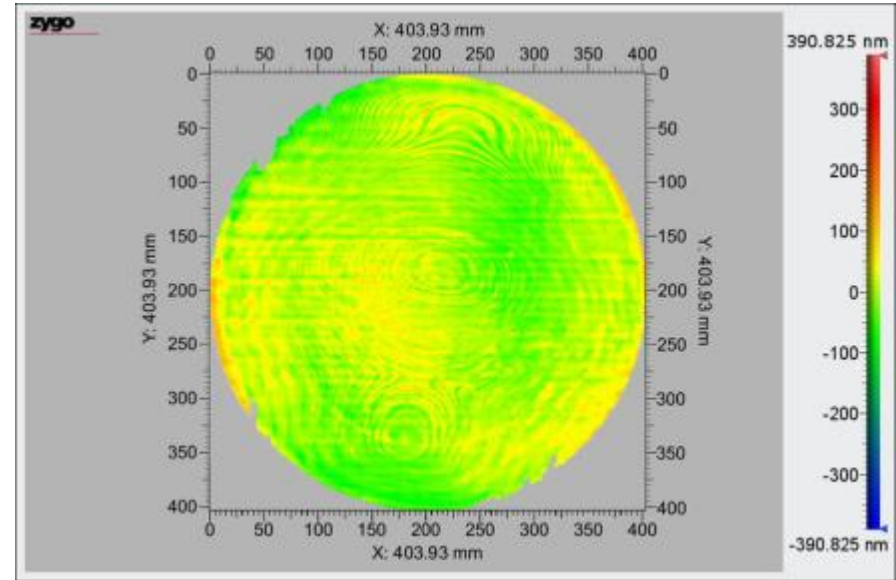
Large scale figuring results: optic #001/2

Initial figure error



PV: 780 nm PVr: 723 nm RMS: 137 nm

Residual figure error

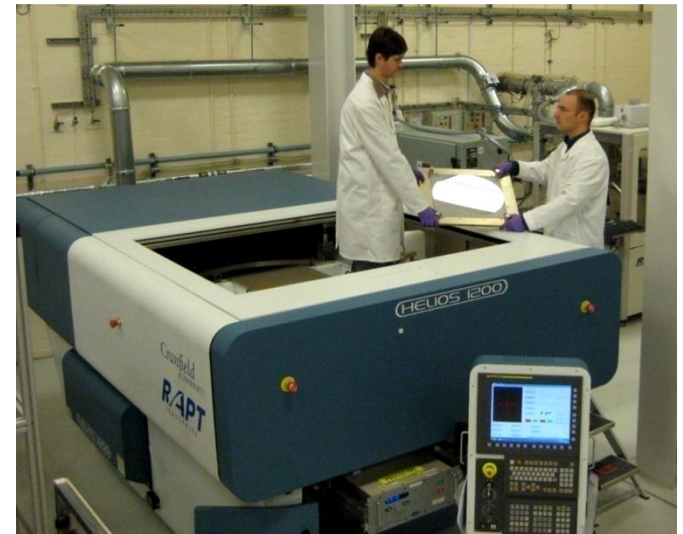
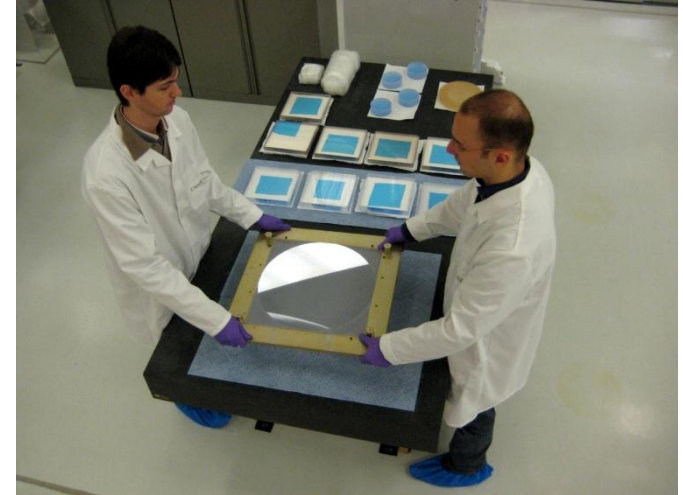


PV: 350 nm PVr: 230 nm RMS: 31 nm

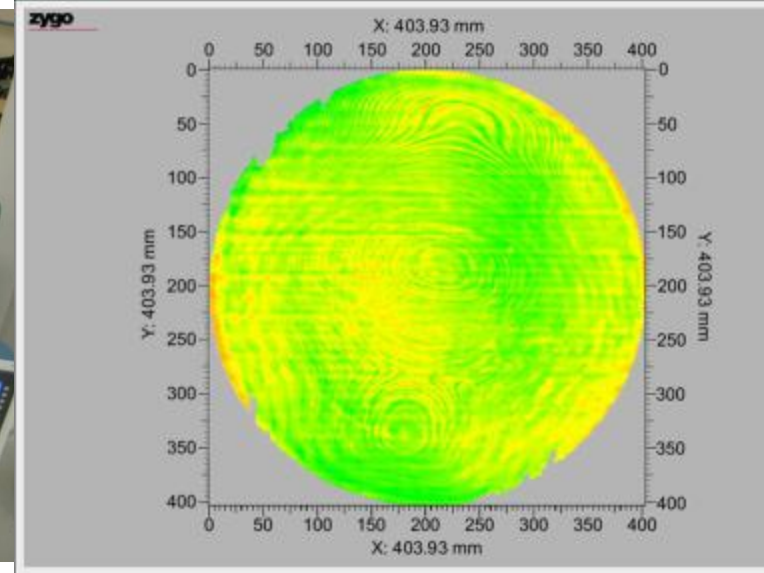
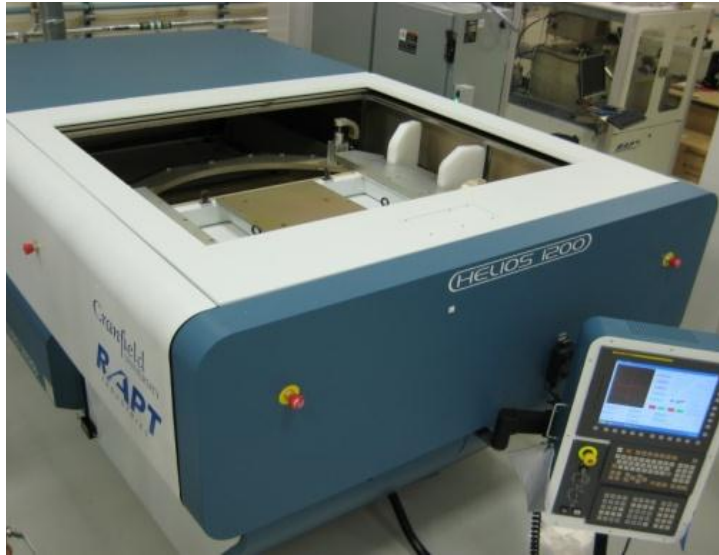
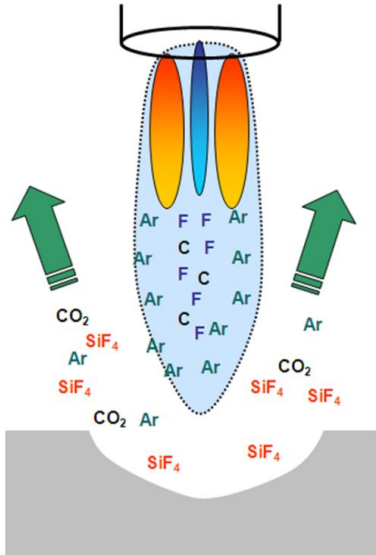
- Mean processing time: 49 min – two iterations → **total processing time 1.5 hours**
- Residual figure error: 31 nm rms
- 77% overall convergence

RAP processing rate

- Removal depth of $1\mu\text{m}$
- 420 mm x 420mm surface
- 2 iteration process
- Average MMR $1.5\text{ mm}^3/\text{min}$
- Figuring time ~ 3 hours
- x10 times faster than IBF



Reactive plasma summary



Processed materials:

- Fused silica
- ULE
- SiC
- Silicon
- Borosilicate

RAPT Machine

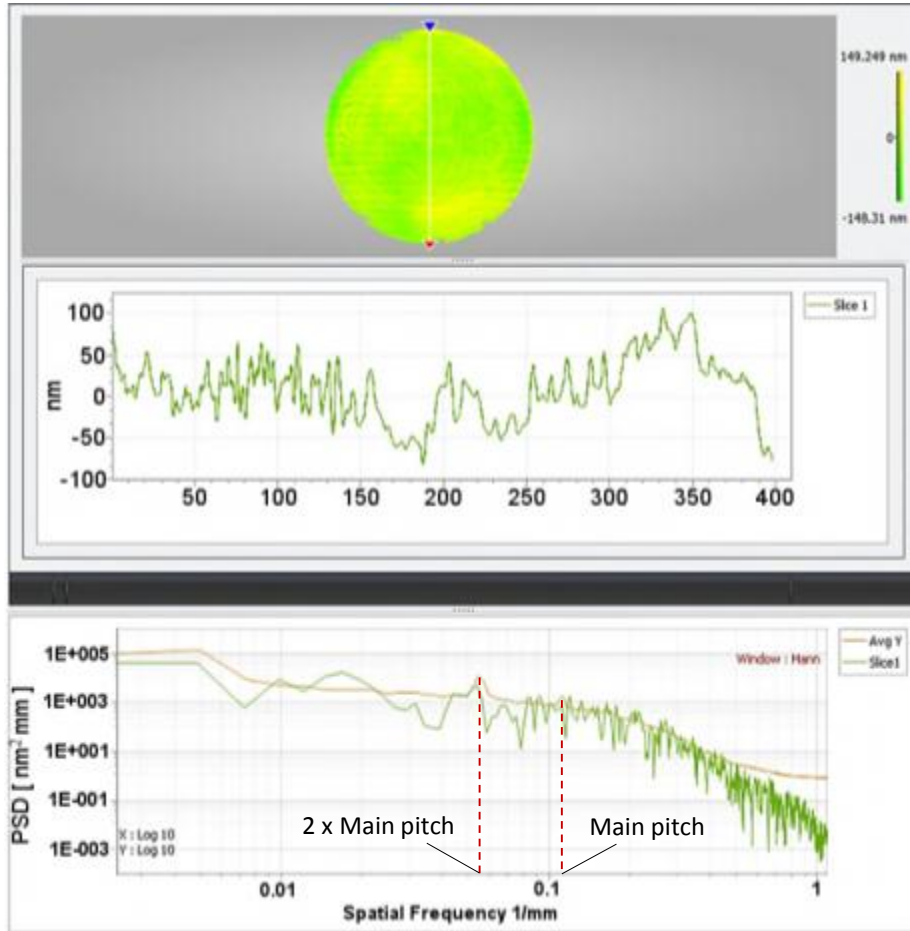
- 1.2 m capacity
- 3 axes CNC through Fanuc 30i
- Low cost operation
- Compact machine size

Processing capability

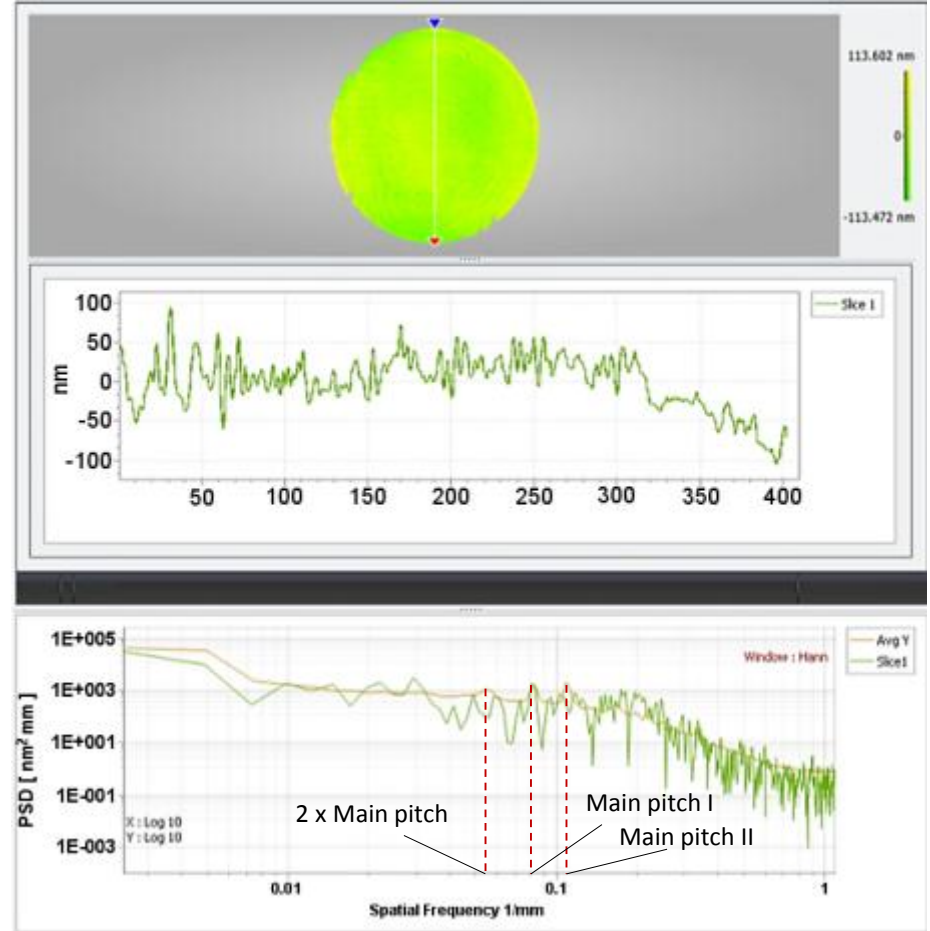
- < 30nm RMS
- 10 hours per metre²
- 400mm mirror in 2 hours

PSD Analysis

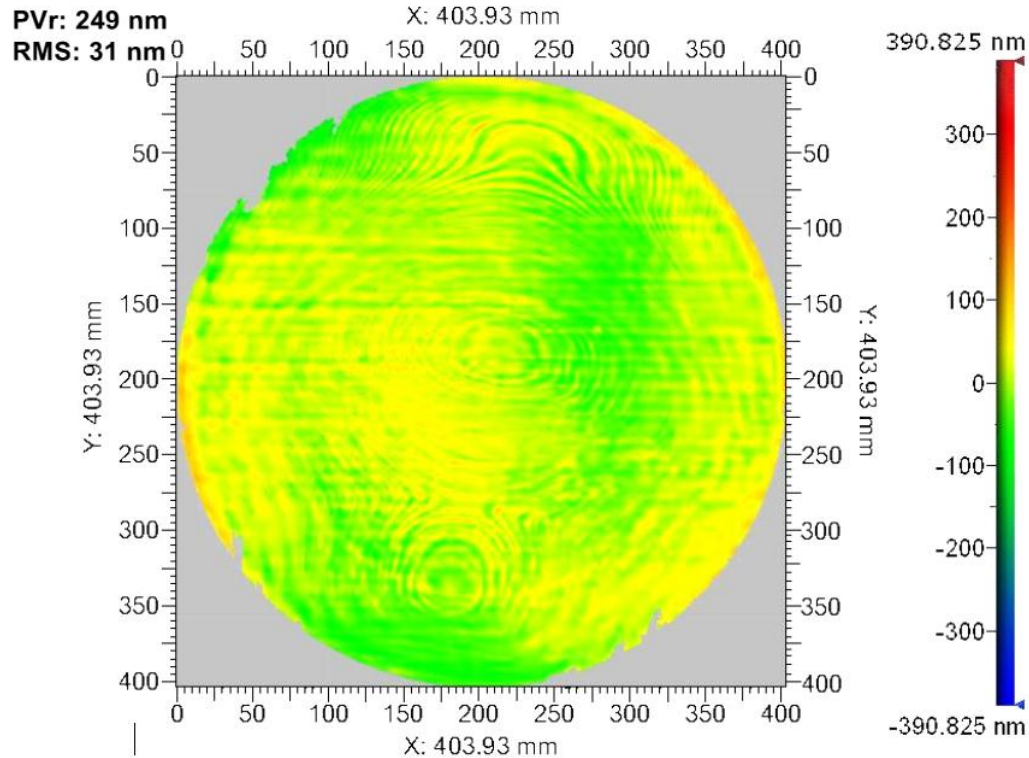
AFTER FIRST FIGURE CORRECTION



AFTER SECOND FIGURE CORRECTION



Present research focus



Reduce the MSF structures

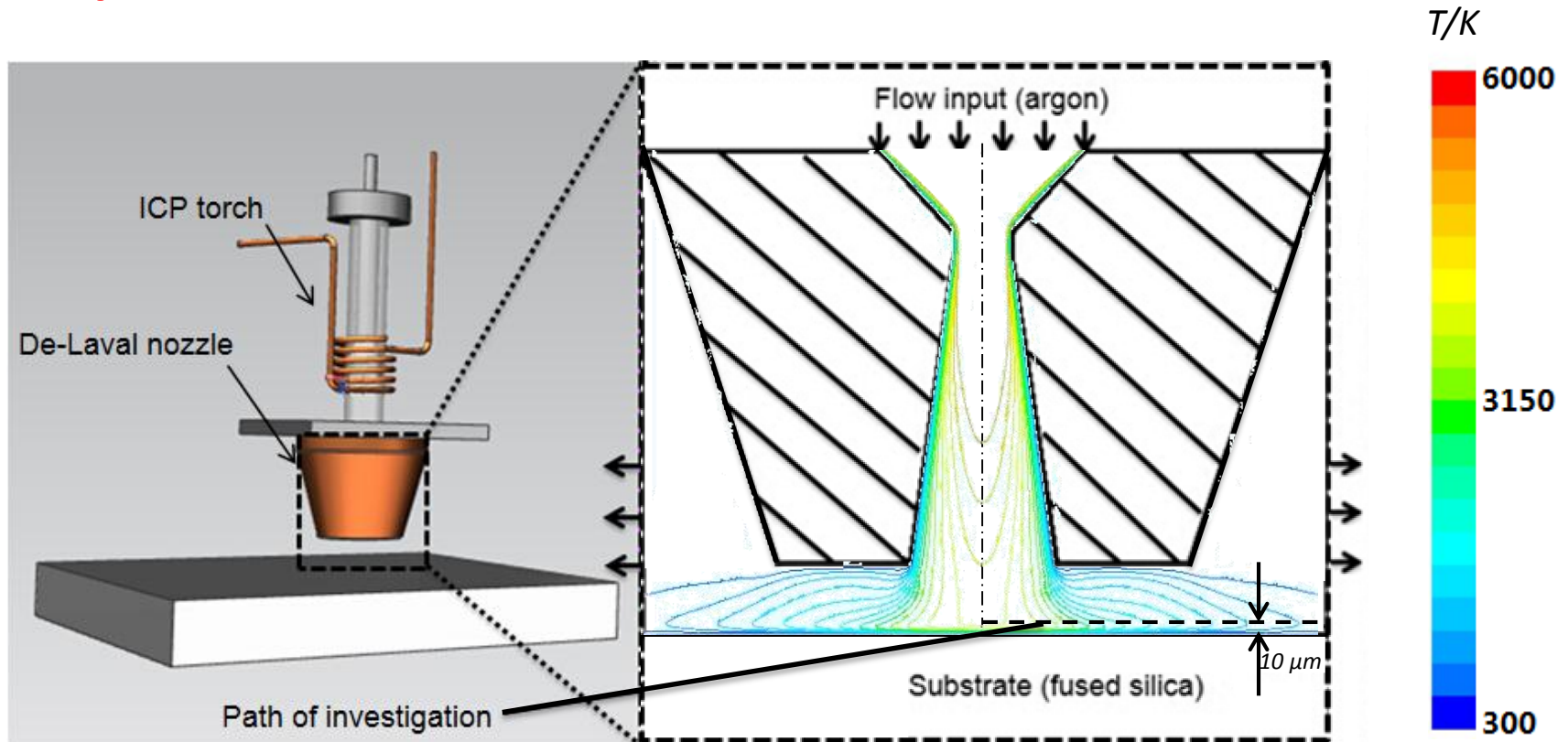
*(Results carried out by **Castelli** [12])*

Ref:

[12] Castelli M. Advances in Optical Surface Figuring by Reactive Atom Plasma(PhD thesis), Cranfield University, 2013.

Thermo-chemical CFD simulation *Cranfield* UNIVERSITY

Temperature distribution



Overview of the CFD investigation.

3D drawing of the plasma figuring torch (left);

2D CFD simulation illustration of flow temperature in the nozzle (right).

- Freeform grinding 1ft² per hour is doable
- Error correction enables <1 um RMS form (Even for thin LW substrates)
- Plasma processing is promising to alleviate bottle-neck surface figuring process stage
- Plasma figuring at 1ft² per hour to 30nm RMS is already doable
- Plasma figuring at 1ft² per hour to 10nm RMS is our next milestone

Acknowledgements

UK's Engineering and Physical Sciences Research Council

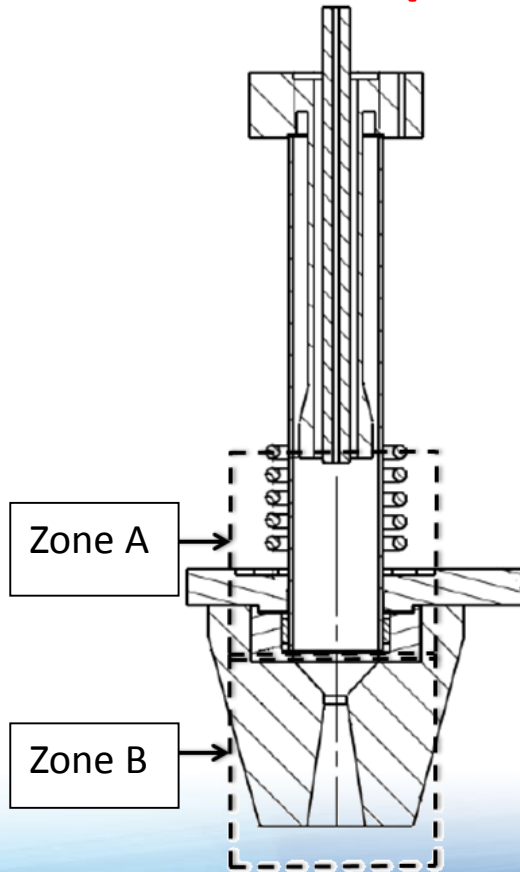
UK's Astronomy Technology Centre

McKeown Precision Engineering Foundation

Collaborators: Qioptiq Ltd, G&H plc, Airbus Space and Defence, SSTL, ESO, ESA, Fanuc, RAPT Industries, University of Cambridge, Cranfield Precision, Optic Glyndwr, UCL, Zeeko, Aerotech

CFD simulation

Model set-up



*Schematic diagram of calculation areas
(Picture from Jourdain)*

Domains: (Zone B)

Based on the ICP torch and De-Laval nozzle made by RAPT

Assumptions:

1. A one-fluid model;
2. In local thermal equilibrium (LTE);
3. Negligible EM field calculations and chemical equilibrium;
4. Thermally expansible and mechanically incompressible;
5. Fluid: axisymmetric, uniform, steady and turbulent plasma with negligible viscous dissipation.

Boundary conditions:

Stage	Parameter	Input value
Inlet	Velocity	25.76 m/s (from calculation)
	Temperature	6000K (based on [8])
	Pressure	101280pa (from calculation)
Wall	Temperature	350K (from estimation)
Outlet	Pressure	101325pa (room pressure)
	Temperature	300K (room temperature)

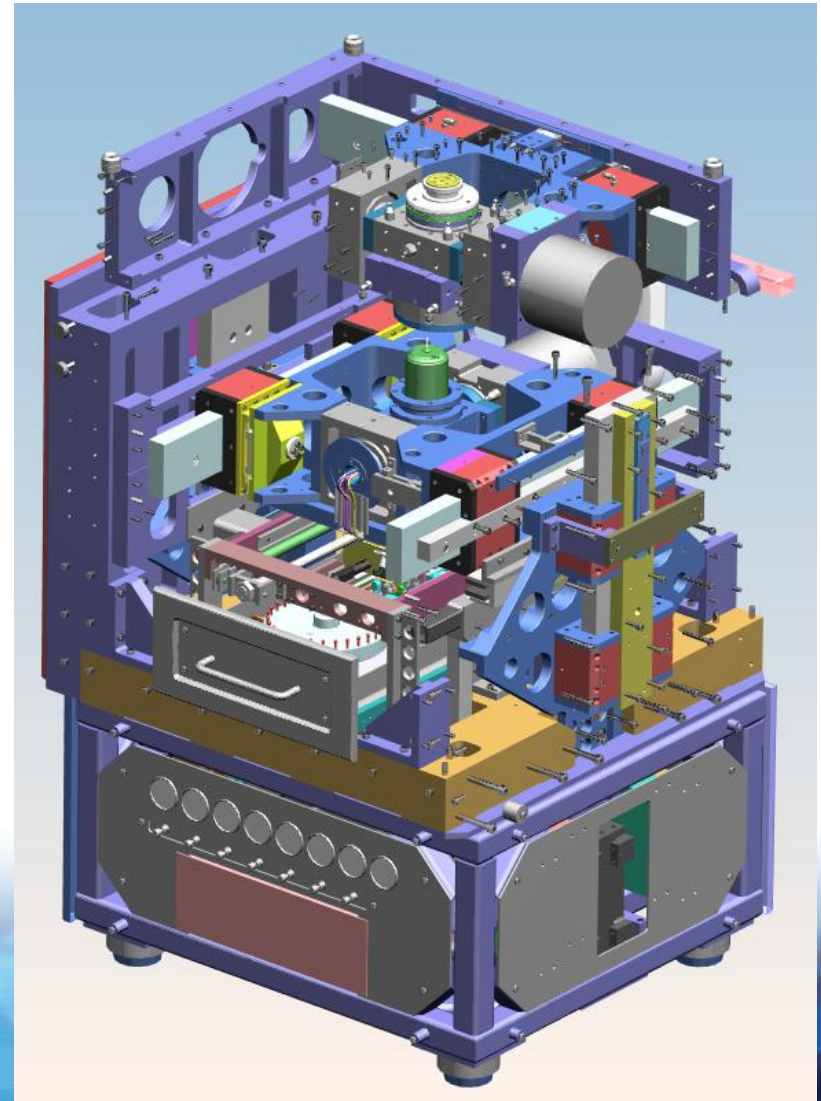
μ 4 diamond machining system

Fully automated & integrated:

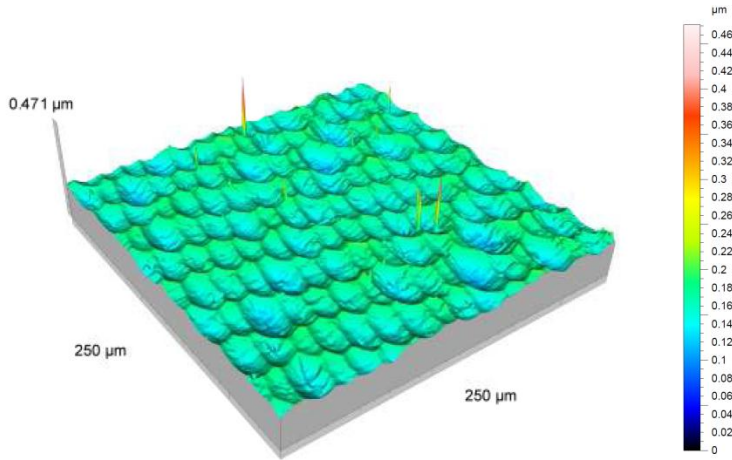
- 4 axis diamond turning
- 5 axis diamond milling
- Tool loading
- Workpiece loading

Machine size and supply

- 0.6m x 0.6m x 1.0m, portable
- Fully integrated control electronics
- single-phase supply “plug-and-play”
- chilled water and compressed air

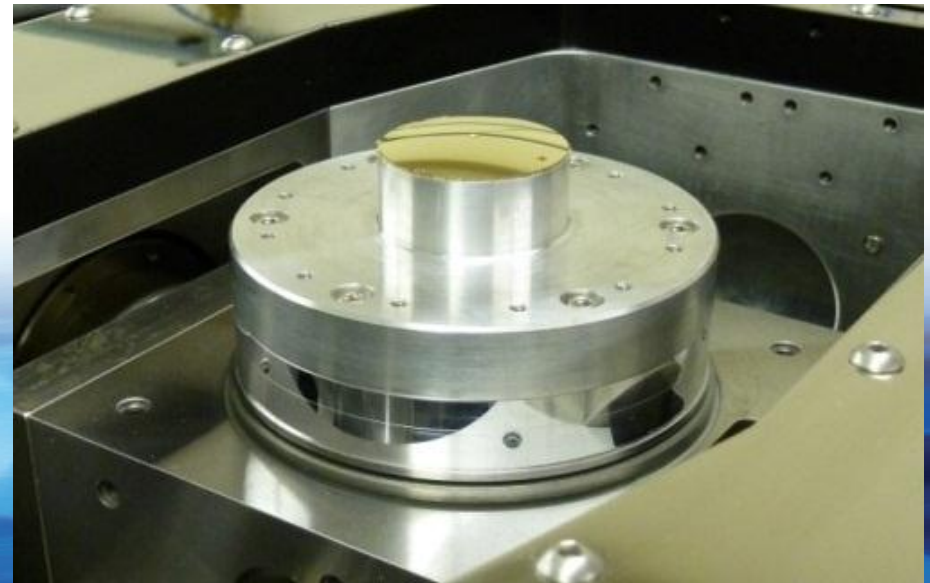


$\mu 4$ diamond machining system

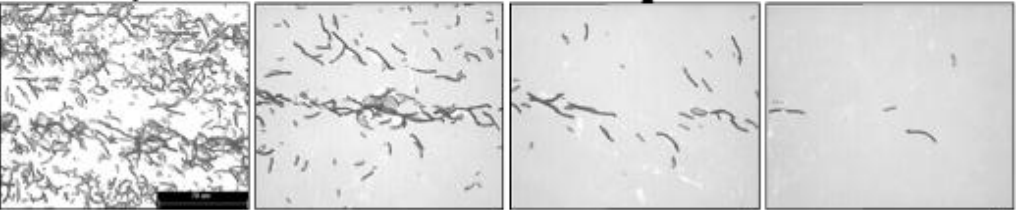
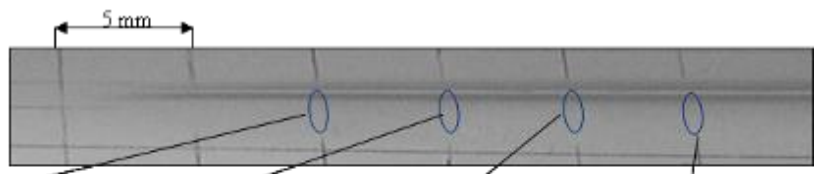


Tests in brass

Roughness: 3nm Ra, 6nm Sa



BoX[®] Induced Sub-surface Damage

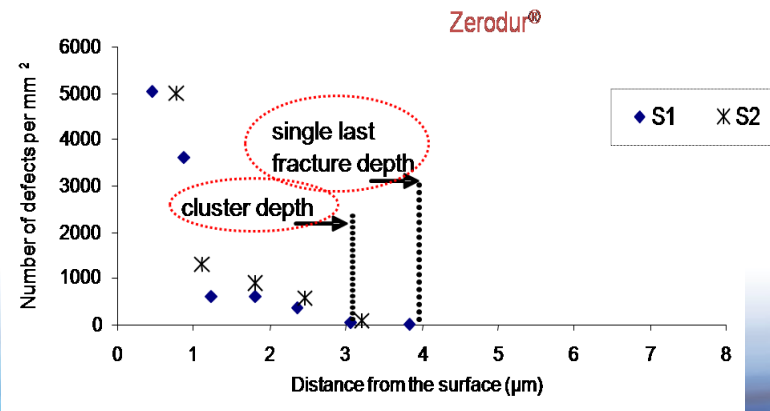


10mm – 0.31μm 15mm – 3.14μm 20mm – 5.61μm 25mm – 8.72μm

Evaluation technique:

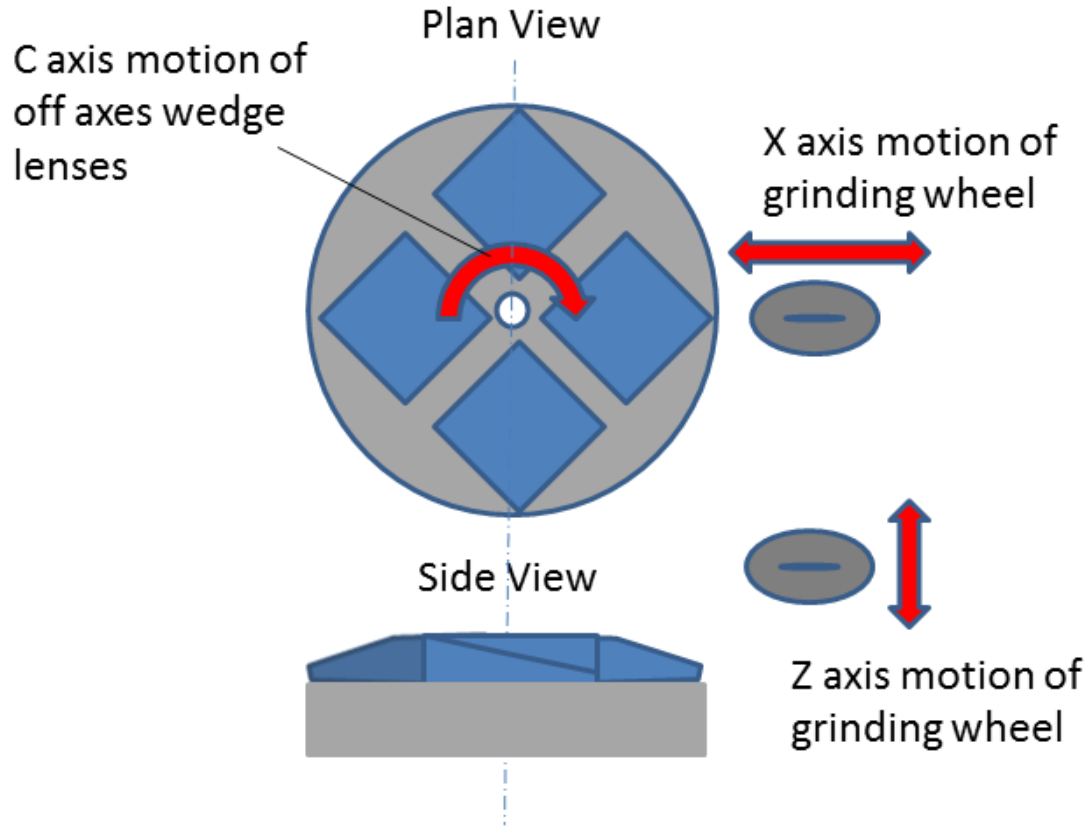
- Polished tapered grooves
- Etched HF, target removal 1μm
- Groove depth - contact profilometry
- Crack observation using optical microscope

Grinding Conditions	Cluster depth (μm)		Last fracture depth(μm)	
	Zerodur [®]	ULE [®]	Zerodur [®]	ULE [®]
Rough cut (D76)	5	8.5	8	18.5
Semi-finish cut (D46)	4	4.5	7.5	9
Finish cut (D25)	3	4	4	8



Ref: Tonnellier, T. et al. 2008, Sub-surface damage issues for effective fabrication of large optics, Proc of SPIE Vol. 7018, pg 701836-1 to 701836-10

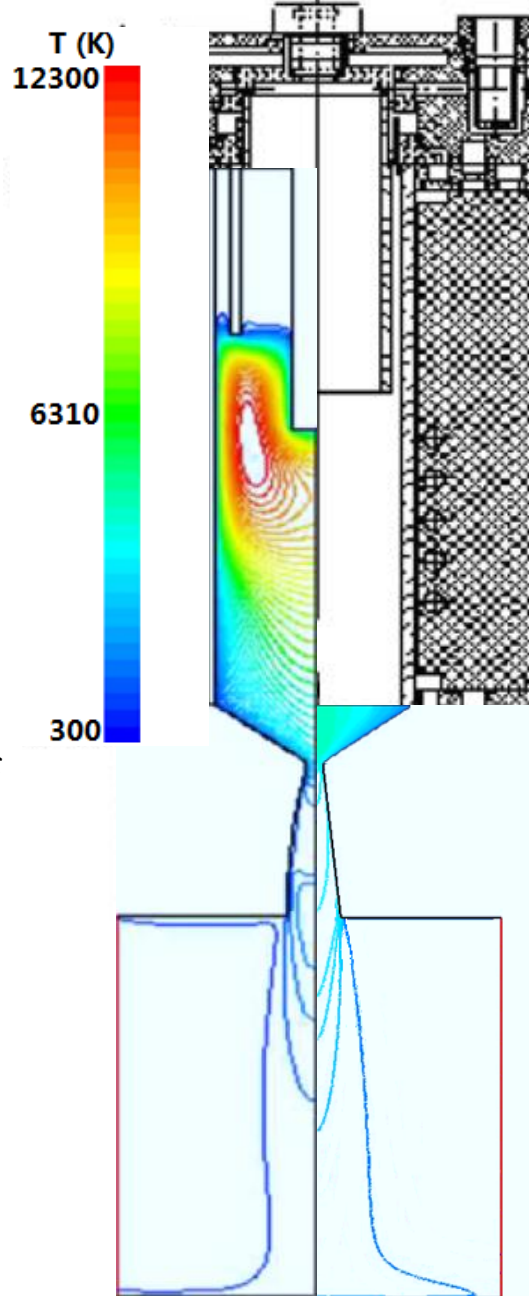
BoX[®] NiF Wedge Optic Lenses



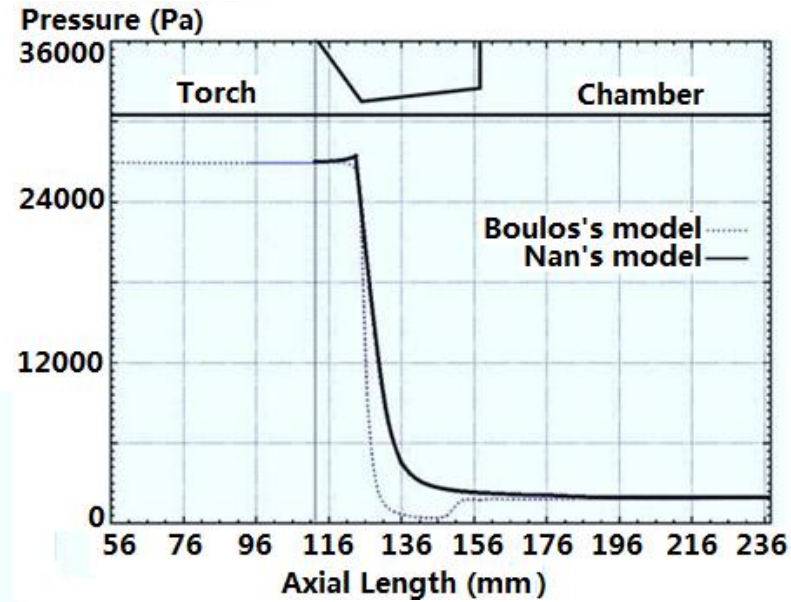
4 off lenses ground
Grinding time: 8 hours
Form accuracy : 1um RMS
SSD : 10 um
Last fracture depth

Background

ICP modelling



Temperature distribution in ICP torch with supersonic nozzle [15]



Axial profile of the pressure along the centreline in [15] and in the repeated trial

Temperature distribution from a repeated trial of the validation

μ4 diamond machining system

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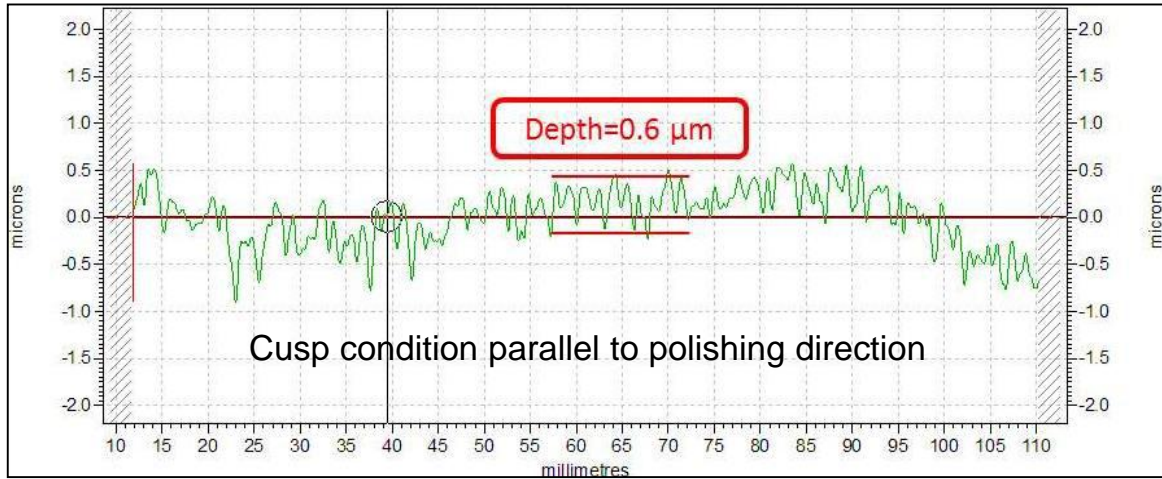
Machine size and supply

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- Fully integrated control electronics
- single-phase supply “plug-and-play”
- chilled water

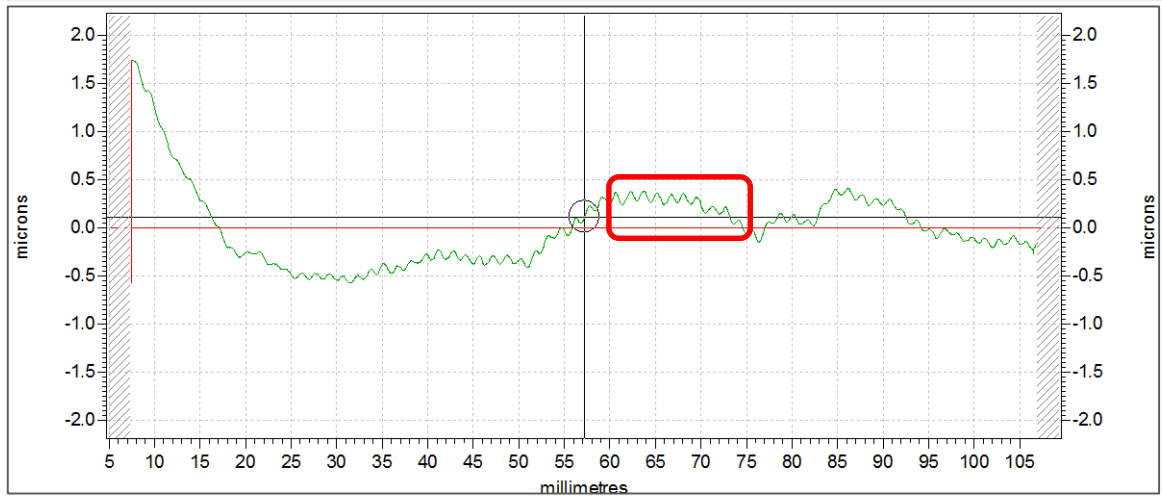




before
polishing



after 4
polishing
runs



after 9
polishing
runs

